

# Active Pixel Sensors in high-voltage CMOS technologies for ATLAS

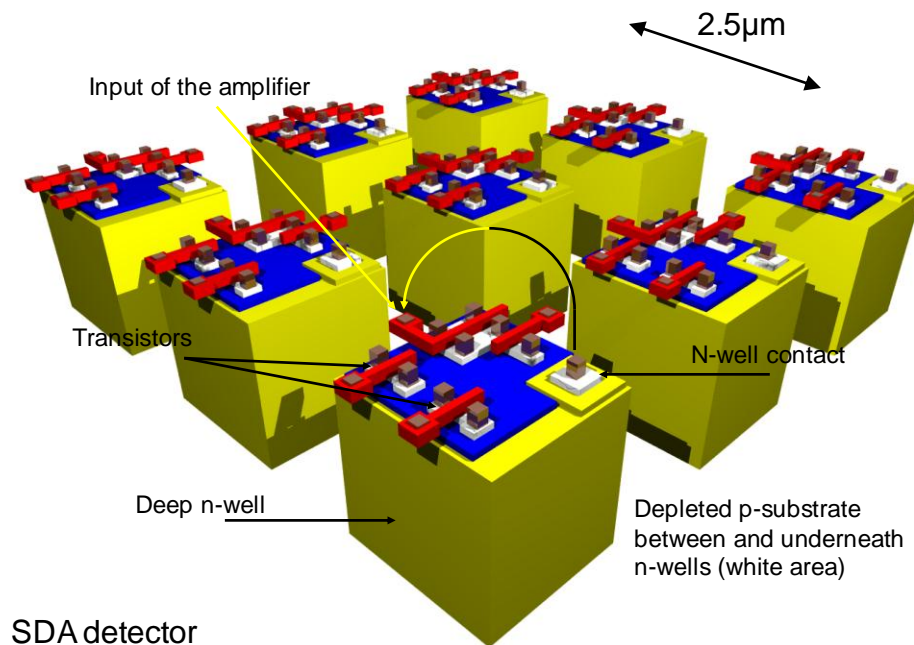
Ivan Perić

University of Heidelberg, Germany

# Introduction: High-Voltage CMOS Pixel Detectors



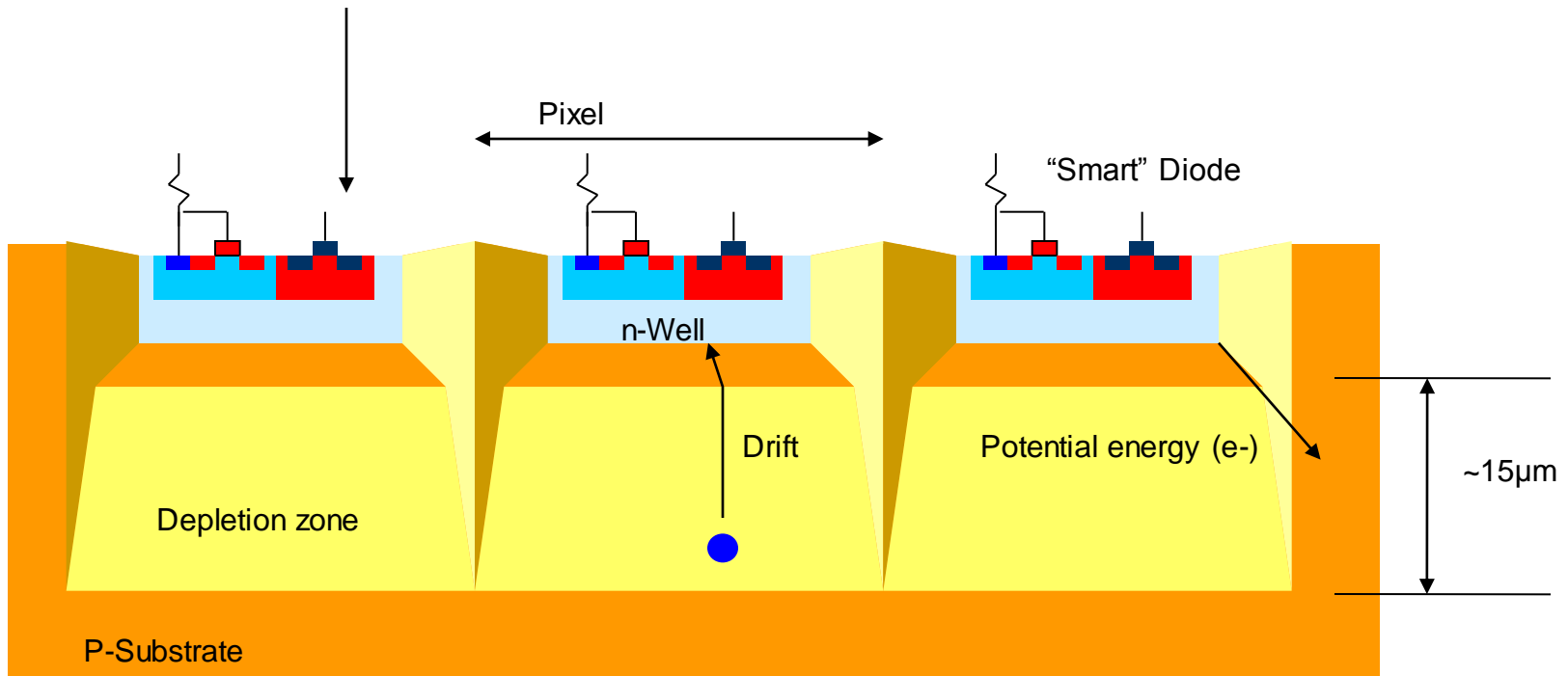
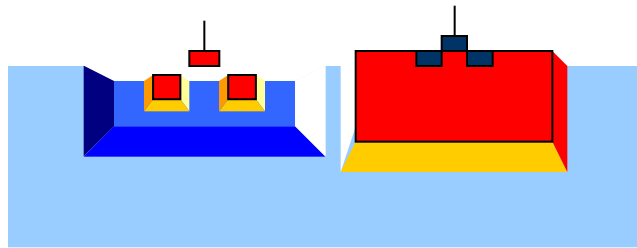
- High-voltage particle detectors in standard CMOS technologies (or “smart diode arrays” - SDAs) are a new detector family that allows implementation of **low-cost radiation-tolerant** detectors with **good time resolution**.
- The deep **n-well in a p-substrate** is used as the charge-collecting electrode
- The entire **CMOS pixel electronics are placed inside the deep n-well**. PMOS transistors are placed directly inside the deep n-well, NMOS transistors are situated in their p-wells that are embedded in the deep n-well as well.
- A typical reverse bias voltage is 60 V and the depleted region depth  $\sim 15 \mu\text{m}$ . **Signal charge collection occurs mainly by drift**.



Nine pixels of the SDA-based pixel detector implemented in 65nm CMOS technology. 3D presentation of the **real layout**.

The use of a high voltage technology is not mandatory for the concept .  
 A SDA structure has been also implemented in a **low-voltage 65 nm technology**  
 Pixel size is 2.5μm!

SDA detector

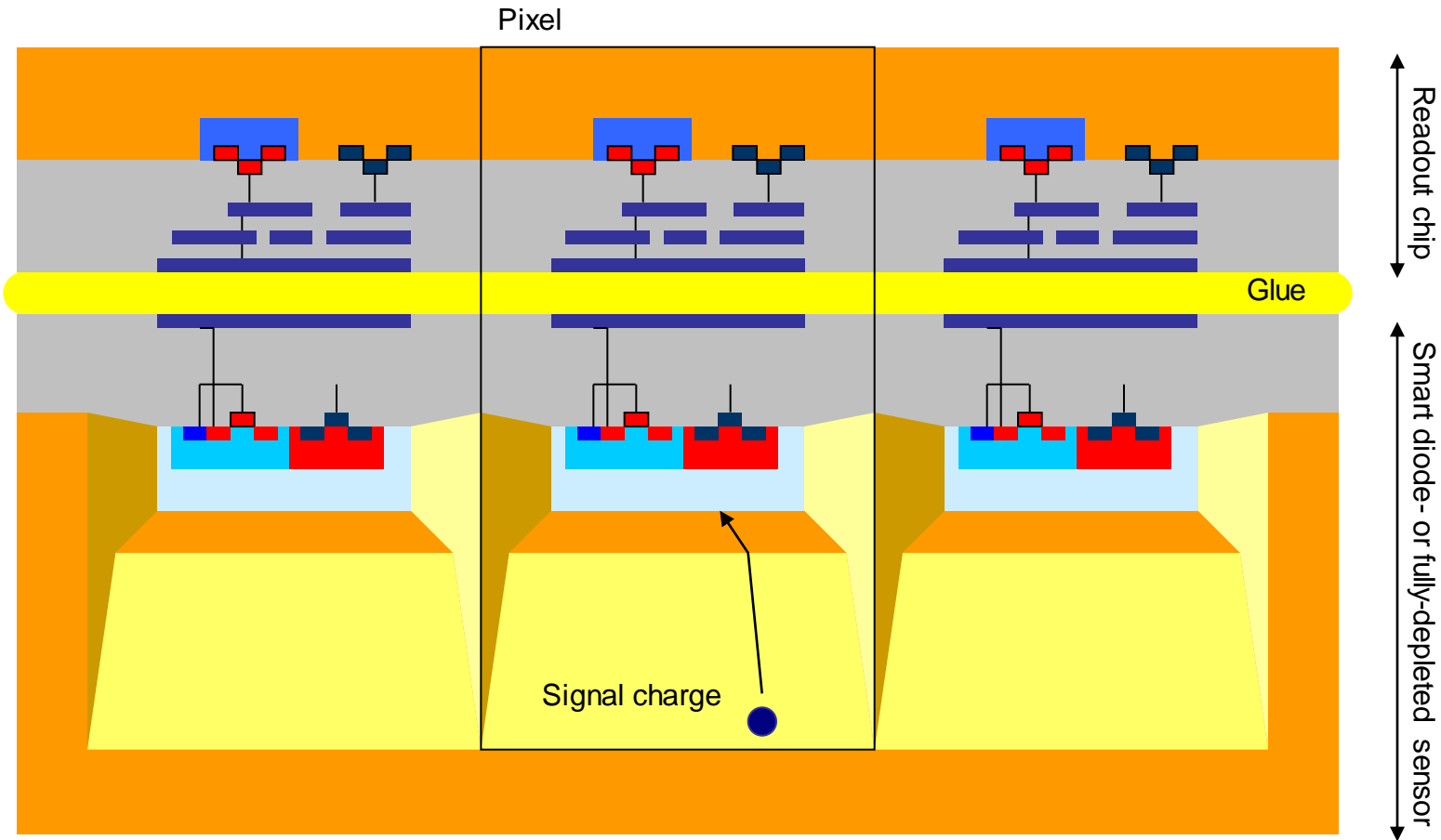


“Smart diode” array

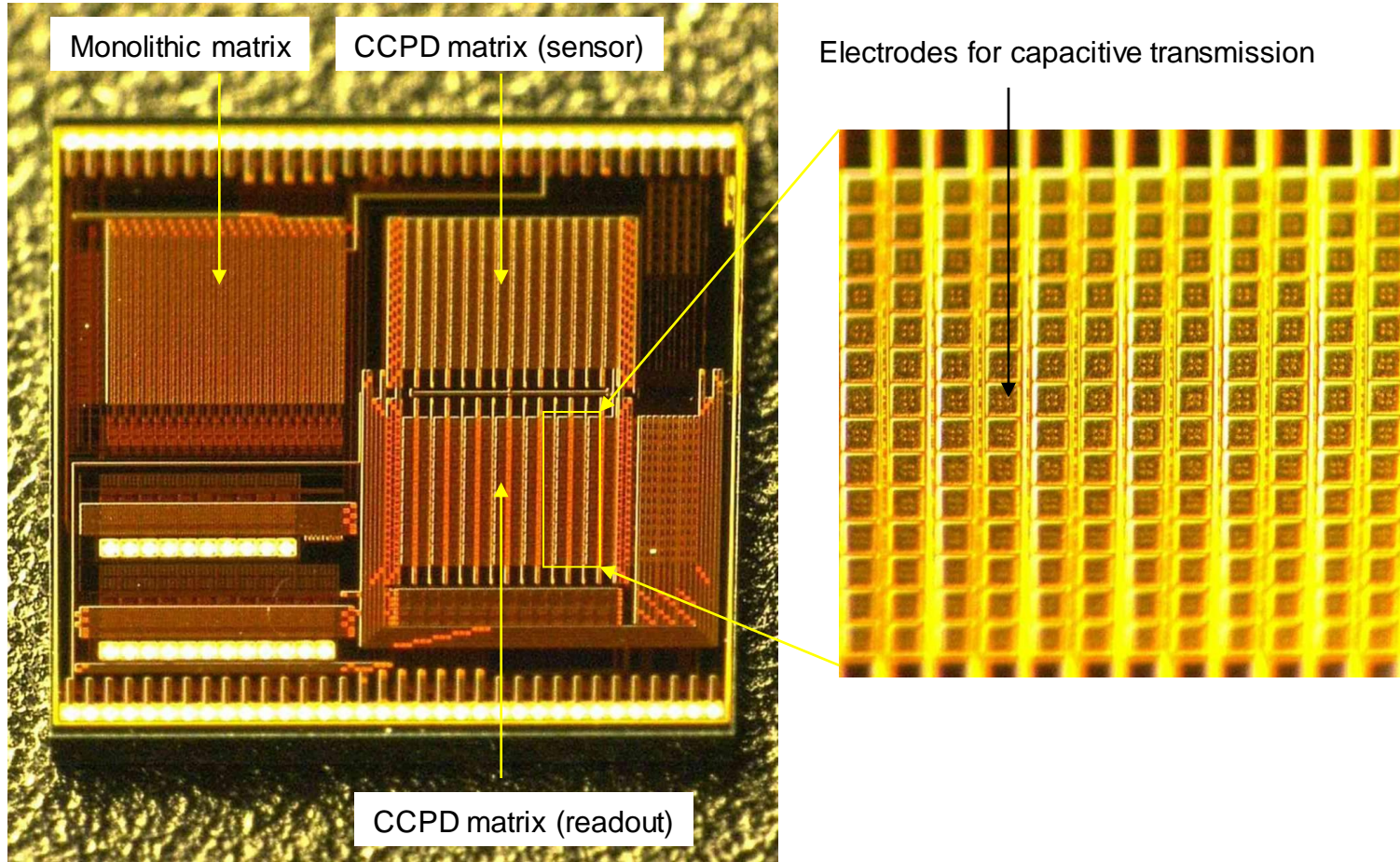
The third dimension illustrates electron potential energy.

- 1) Active sensor
- 2) CMOS in-pixel electronics – “intelligent “detectors.
- 3) Fast signal collection
  - $\sim 15\mu\text{m}$  drift path, 50V
- 4) Thinning possible
  - Since the charge collection is limited to the chip surface, the sensors can be thinned.
- 5) Price and technology availability
  - Standard (HV) technology without any adjustment is used
  - Many industry relevant applications of HV CMOS technologies assure their long term availability.
  - 180nm technology: 160k€ and 1.5k€/8 inch wafer (1 wafer  $\sim 200\text{ cm}^2$ )
  - The structure can be also implemented in many low voltage technologies.
- 6) High tolerance to non-ionizing radiation damage
  - High drift speed
  - Short drift path
- 7) High tolerance to ionizing radiation
  - Deep submicron technology
  - Radiation tolerant design can be used.
  - PMOS transistors, that are more tolerant to radiation, can be used as well in contrast to standard MAPS.

# Capacitive Coupled Pixel Detectors - CCPDs

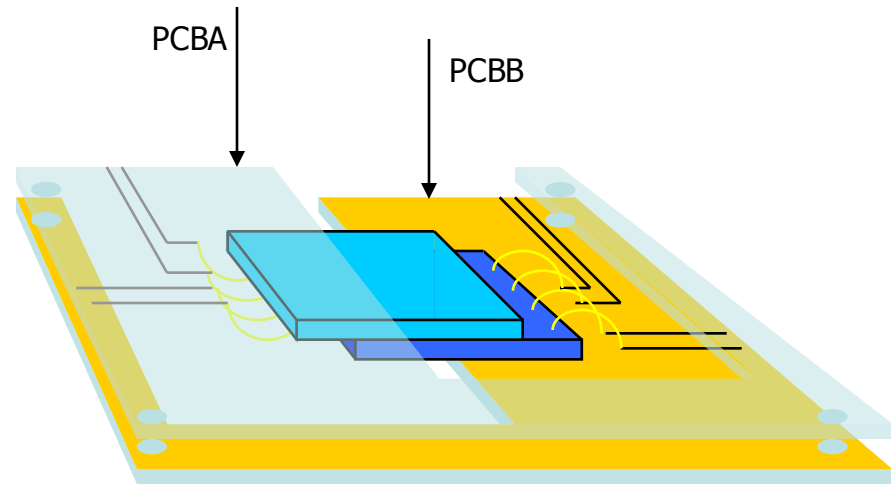
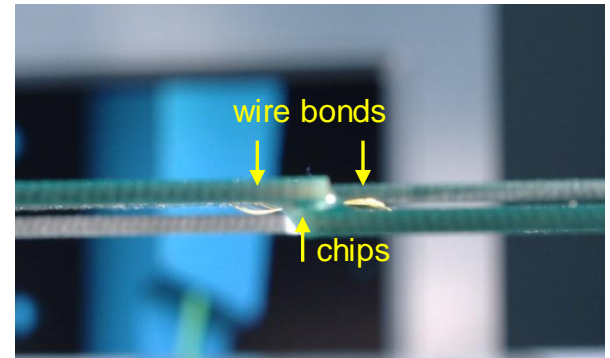
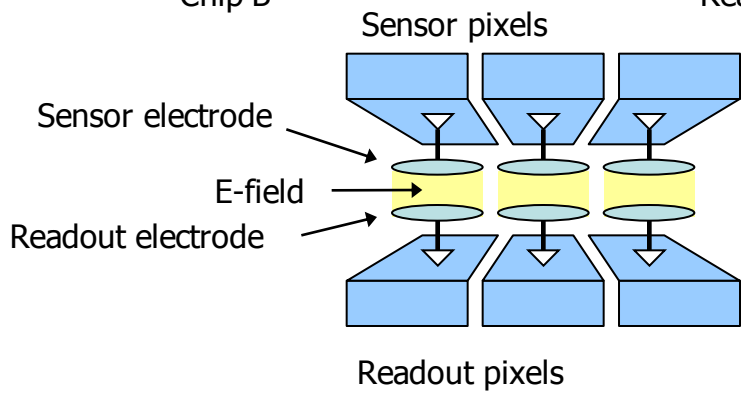
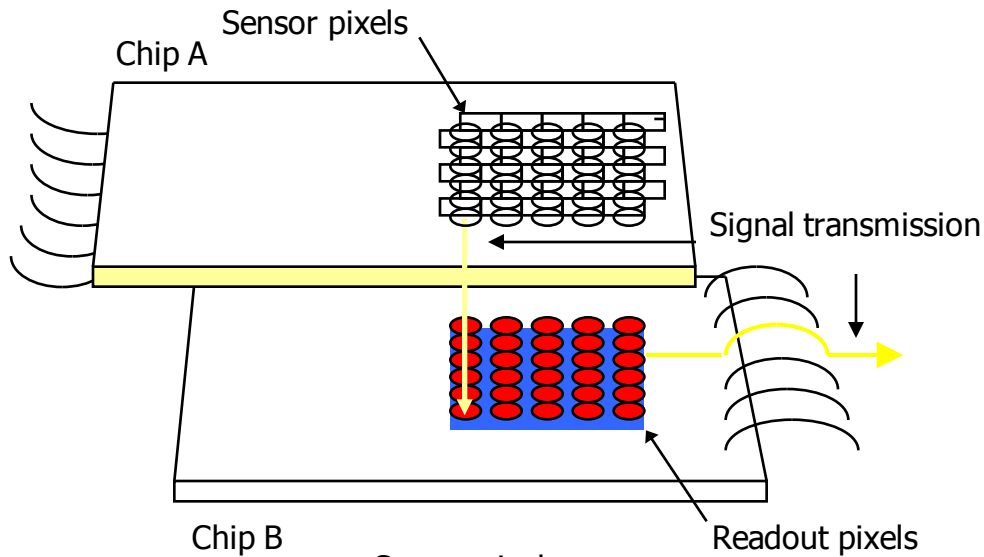


The signal from sensor chip is **transmitted capacitively** to the readout chip.  
 The sensor and readout chips are flipped and glued .



Sensor and readout matrix implemented as same design (to save costs)

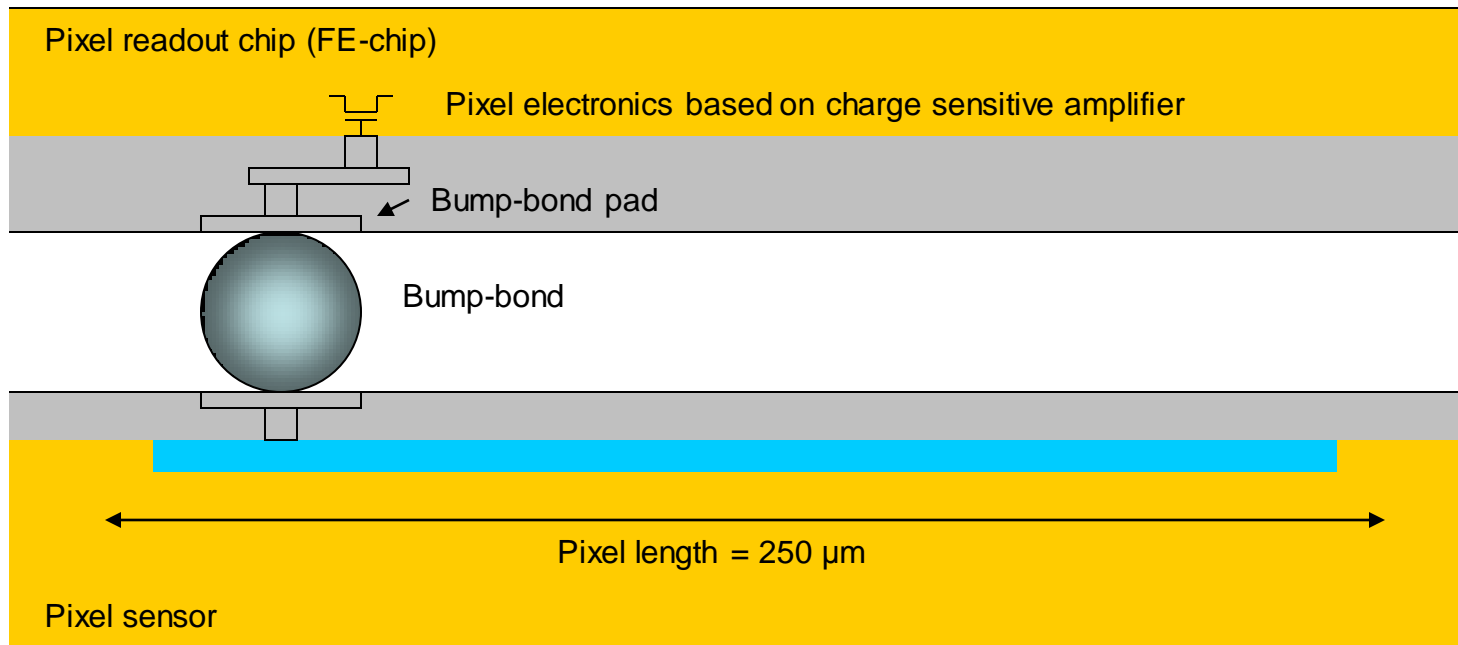




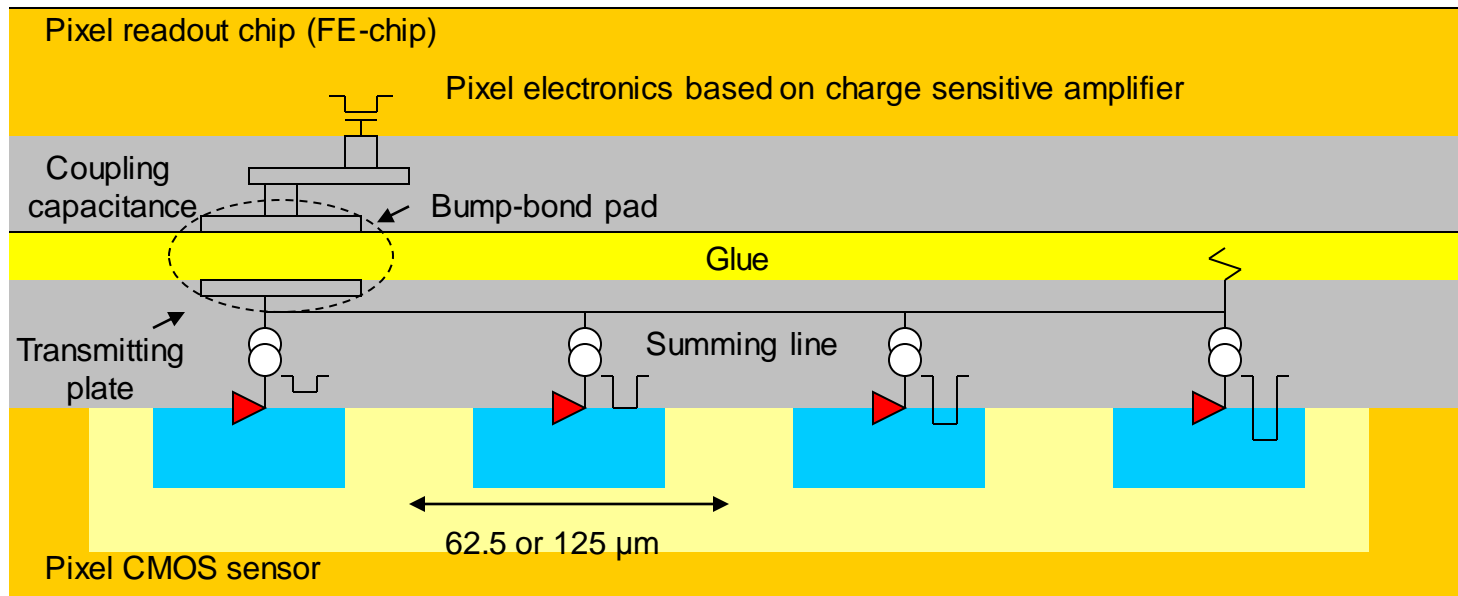
# High-Voltage CMOS Detectors for ATLAS

# CCPD Concept

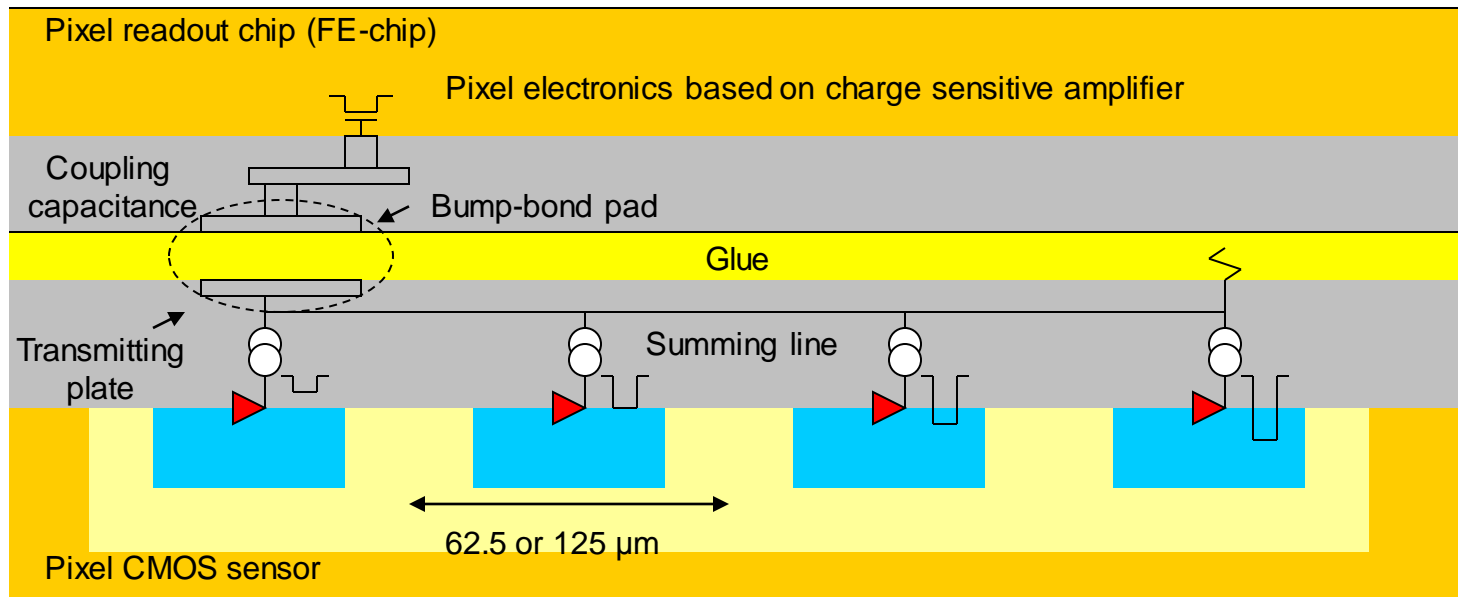
- Replacing the passive diode-based pixel sensor with an “intelligent” pixel sensor implemented in HV CMOS technology.
- Intelligence: the pixels are able to distinguish a signal from the background and to respond to a particle hit by generating an address information.



- The HVCMOS sensor pixels are **smaller than the standard ATLAS pixels**, for instance  $25\mu\text{m} \times 125\mu\text{m}$  - so that several such pixels cover the area of the original pixel.
- The HV pixels contain low-power ( $\sim 5 \mu\text{W}$ ) CMOS electronics based on a charge sensitive amplifier and a comparator.



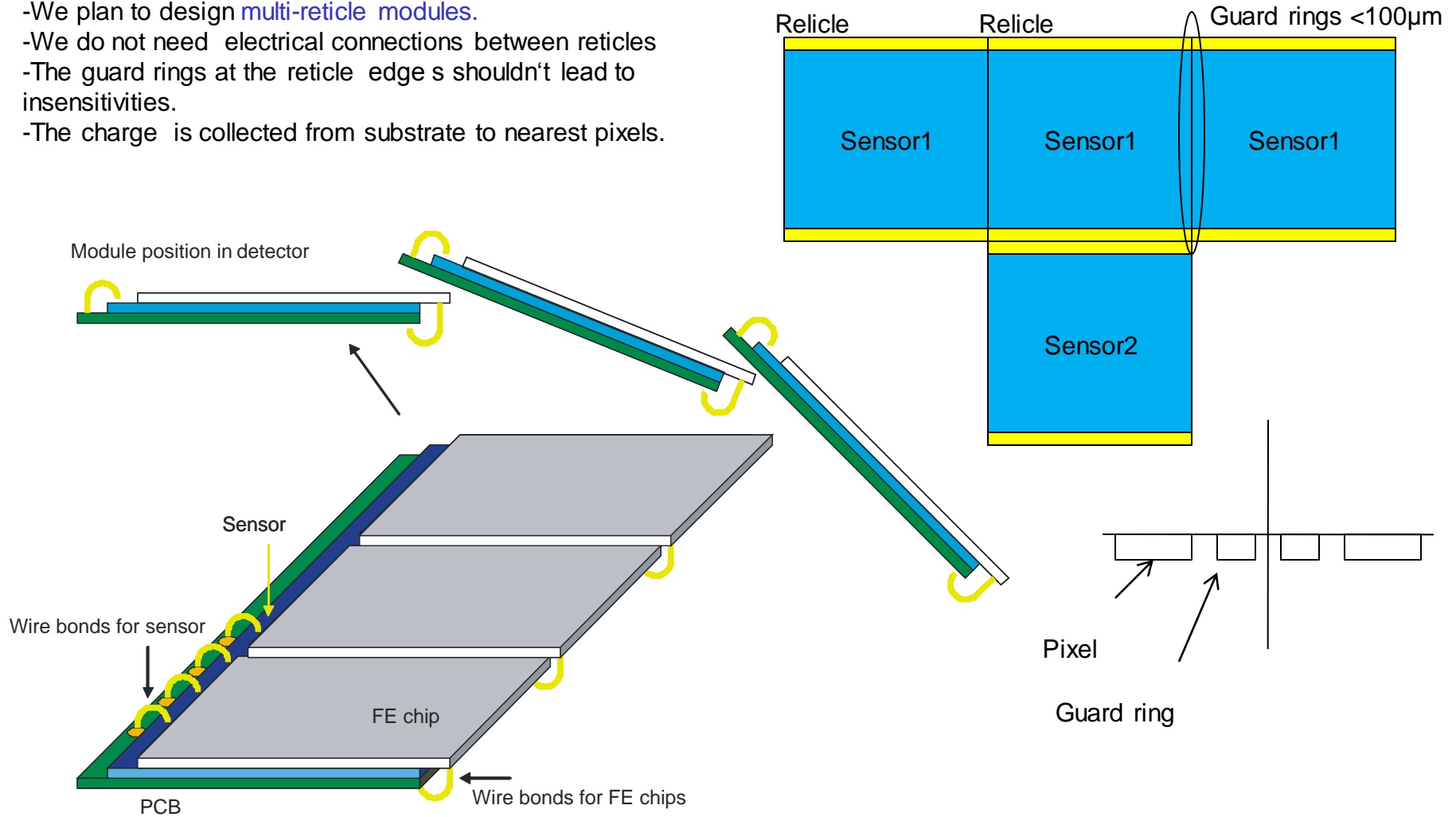
- The electronics responds to a particle hit by generating a pulse.
- The signals of a few pixels are summed, converted to voltage and transmitted to the charge sensitive amplifier in the corresponding channel of the FE chip using AC coupling.
- For comparison and testing purposes, the signal transmission can – in addition to capacitive coupling – also be established by classical bump-bonding.





- Each of the pixels that couple to one FE receiver can have its **unique signal amplitude**, so that the pixel can be identified by examining the amplitude information generated in FE chip.
- In this way, spatial resolution in  $\varphi$ - and z-direction can be improved.

- We plan to design **multi-reticle modules**.
- We do not need electrical connections between reticles
- The guard rings at the reticle edges shouldn't lead to insensitivities.
- The charge is collected from substrate to nearest pixels.



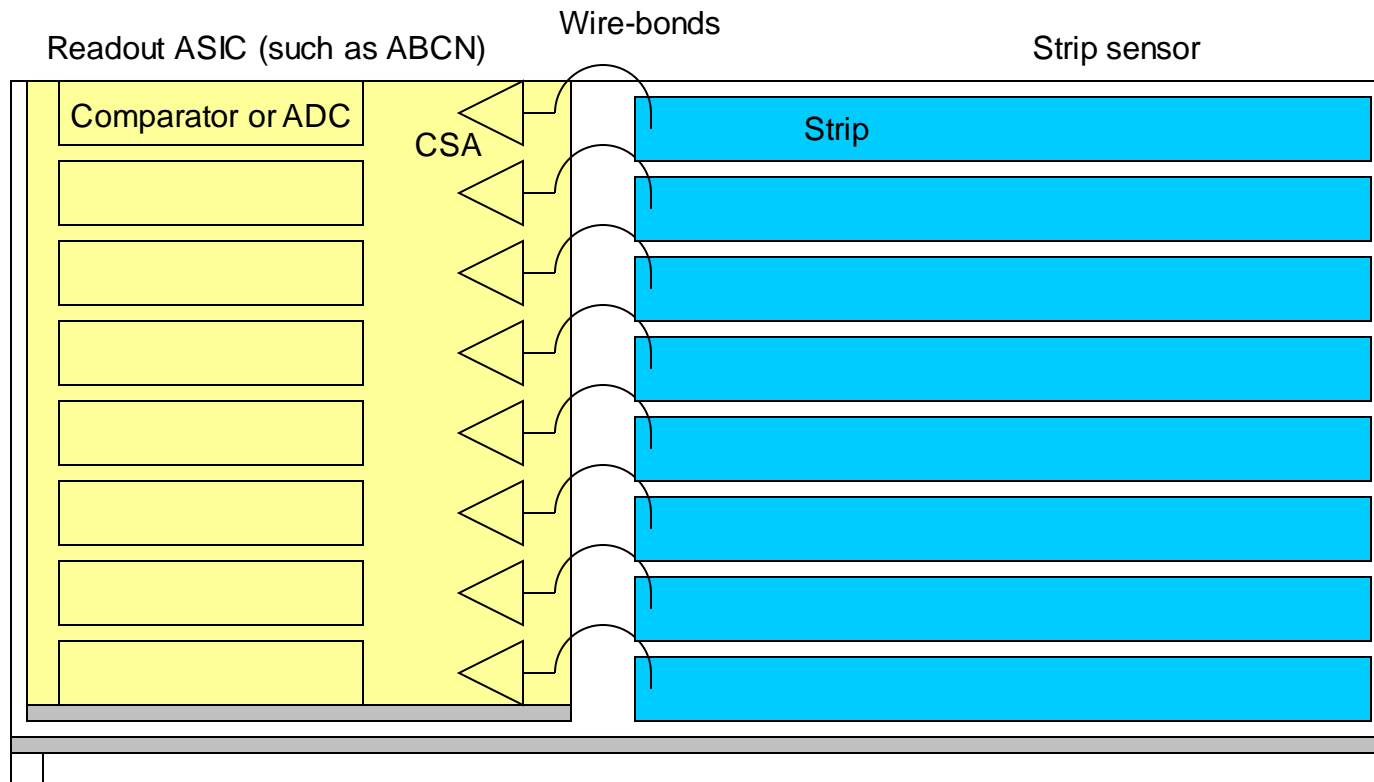




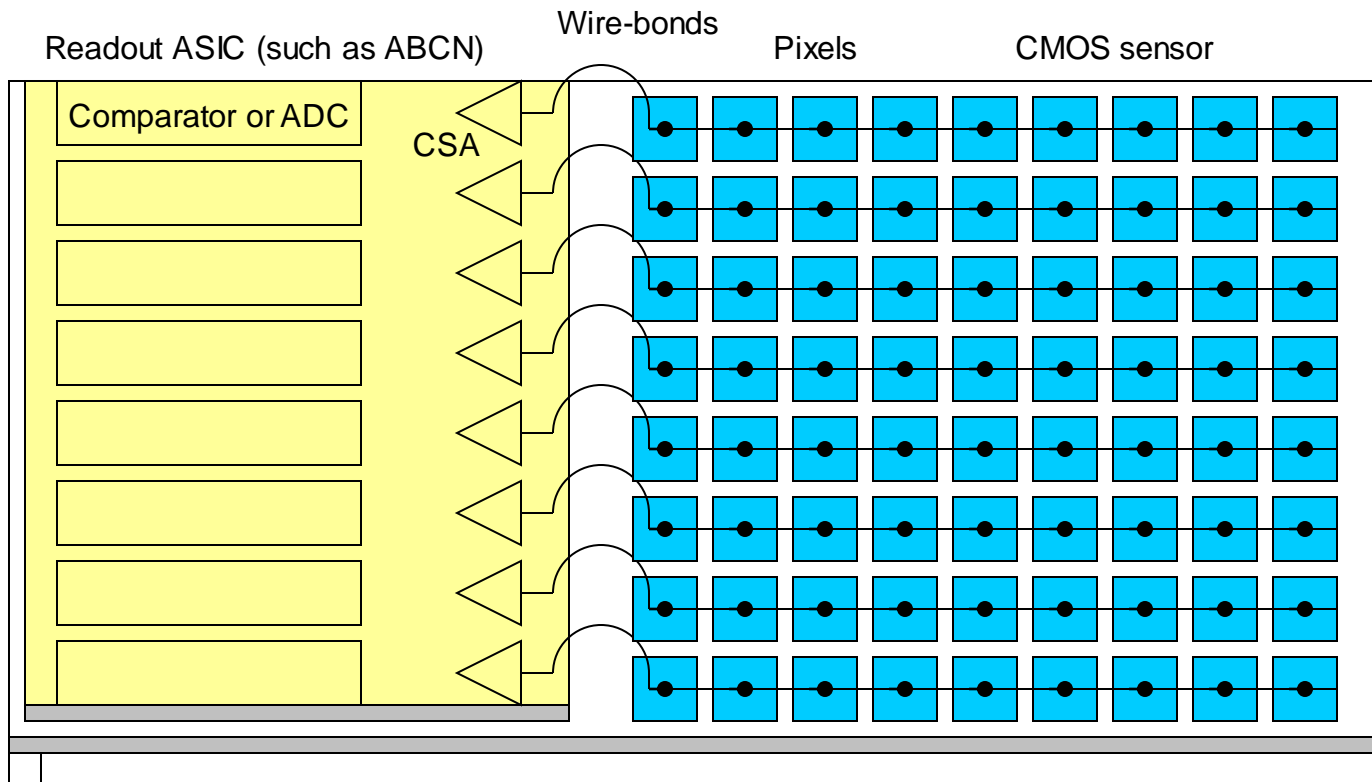
- No need for bump-bond connection between the sensor and readout chip – lower price, better mechanical stability, less material
- Commercial sensor technology – lower price
- No need for bias voltages higher than 60V
- Operation at temperatures above 0C is according to tests possible (irradiations to  $10^{15} n_{eq}/cm^2$ )
- Increased spatial resolution (e.g.  $25\mu m \times 125\mu m$  binary resolution) with the existing FE chip
- Smaller clusters at high incidence angles
- Possibility of sensor-thinning without signal loss. Since we do not use bumps and FE chips can be thinned as well, the amount of material would be very low.
- Interesting choice for other experiments where low-mass detectors are needed such as CLIC, ILC, CBM, etc...

# Strip-like Concept

- Present LHC strip detectors consist of large-area strip sensors that are connected by wire bonds to multi-channel ASICs.

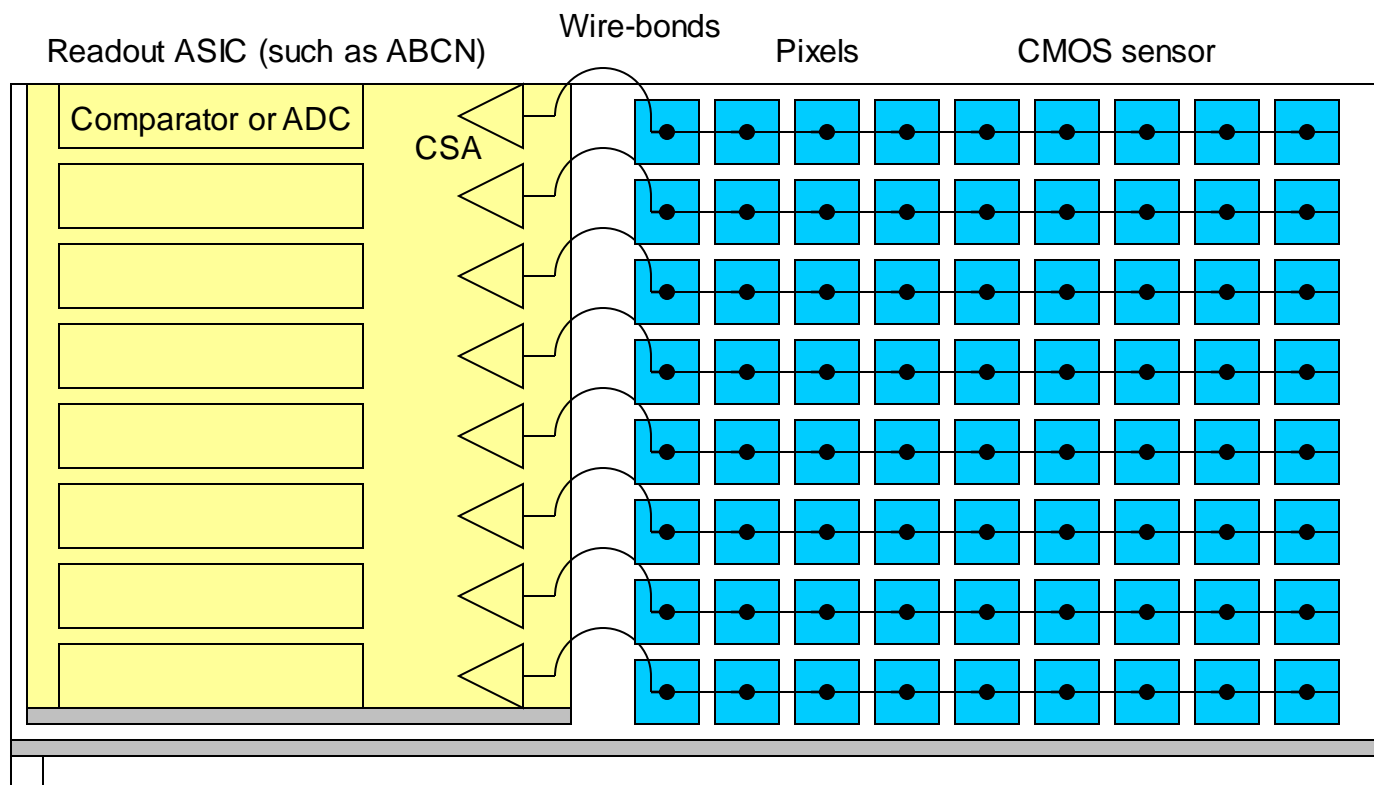
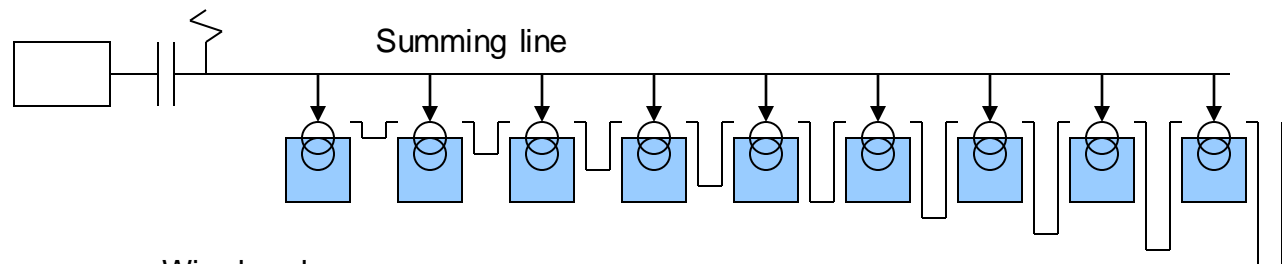


- We replace a strip with a line of pixels in HVCMOS technology.





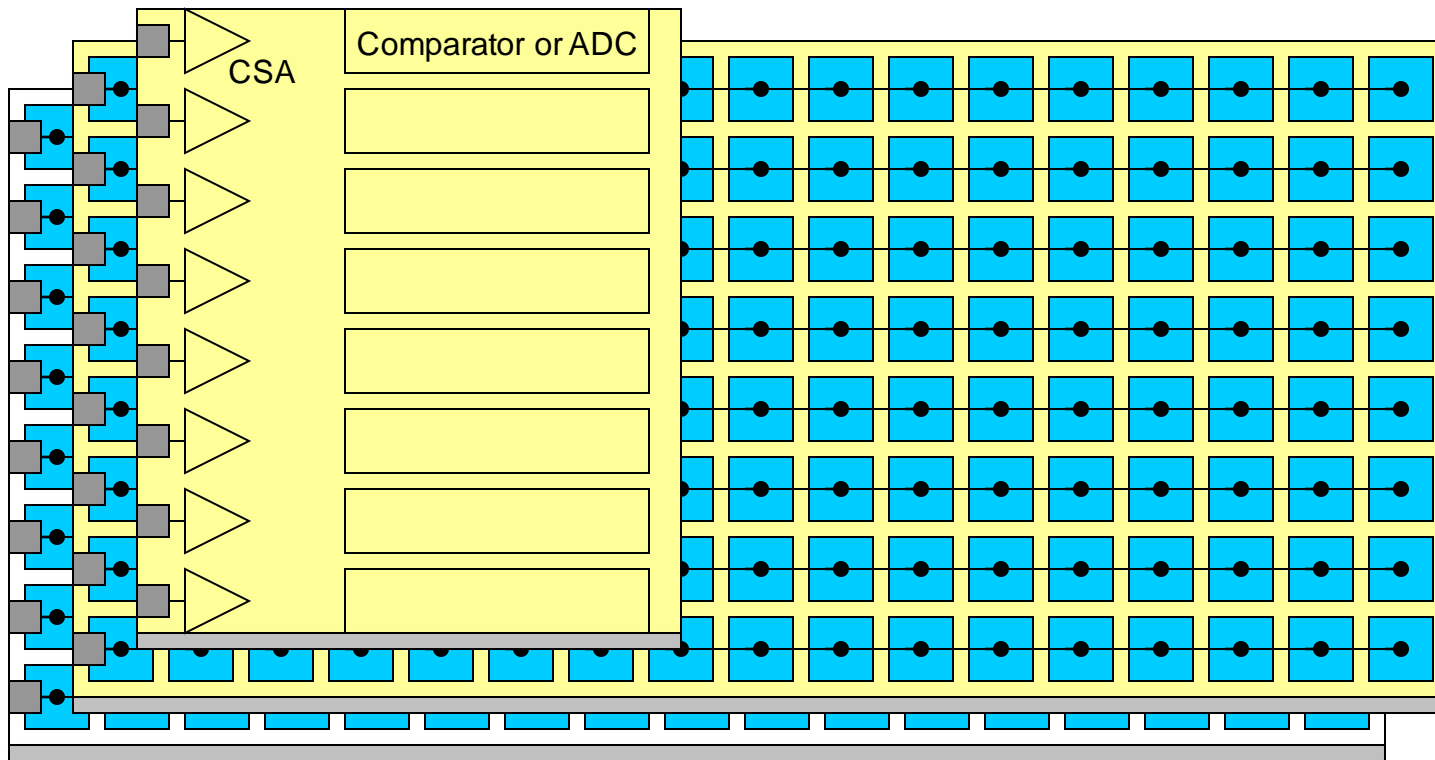
- Every pixel generates a digital pulse with unique amplitude of logic one.
- The pixel outputs are summed, converted to voltage signal and transmitted to readout ASIC.





- A large area CMOS sensor can be produced by stitching several 2cm x 2cm wafer reticles.
- Any arbitrary pixel group pattern is possible.
- **Advantages:**
- Commercial sensor technology – lower price per unit area
- Intrinsic 2D spatial resolution (e.g. 25  $\mu\text{m}$  x 125  $\mu\text{m}$  binary resolution)
- No need for bias voltages higher than 60V
- Operation at temperatures above 0C is according to tests possible (irradiations to  $10^{15} n_{\text{eq}}/\text{cm}^2$ )
- Thinning possible

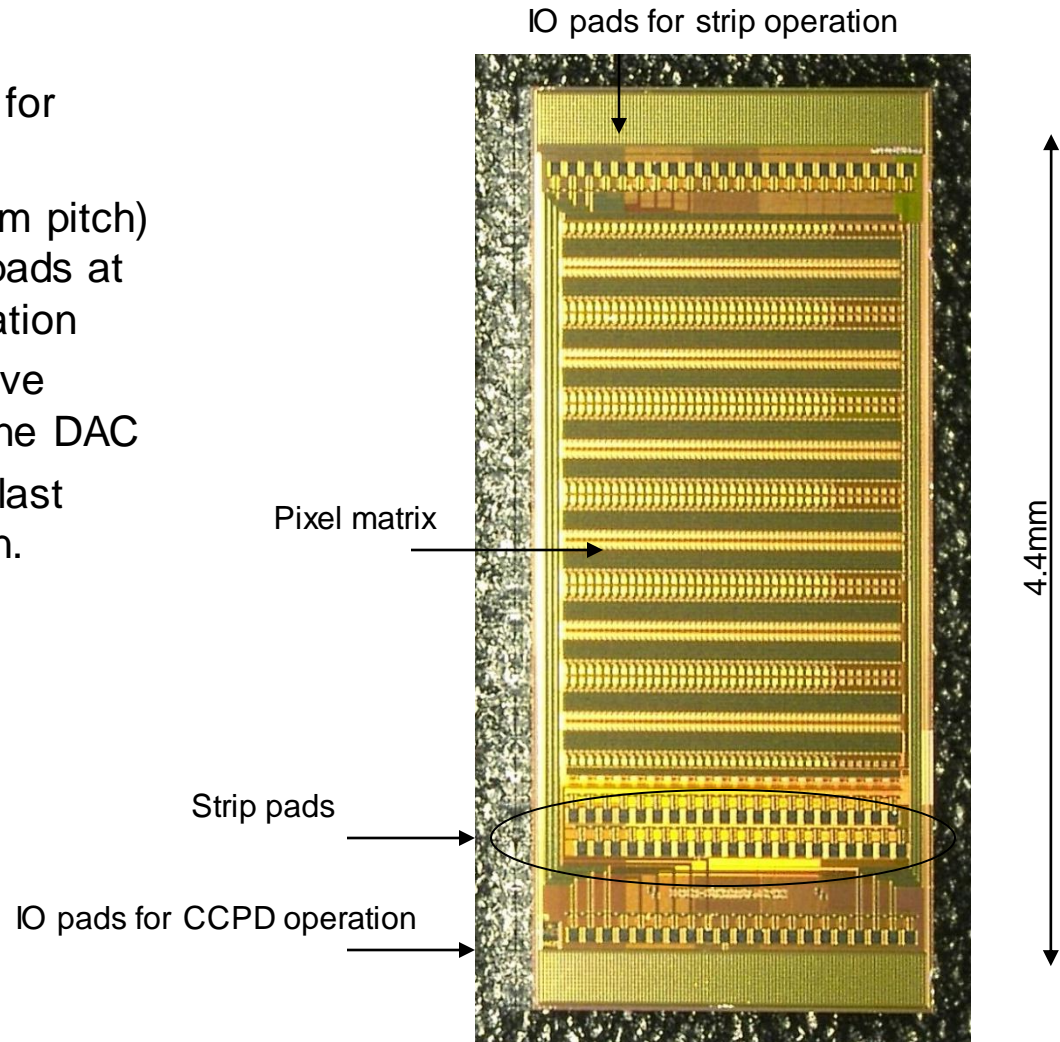
- Simultaneous readout from two 2D sensitive layers. Signals from two sensor layers can be easily combined in a single readout ASIC.

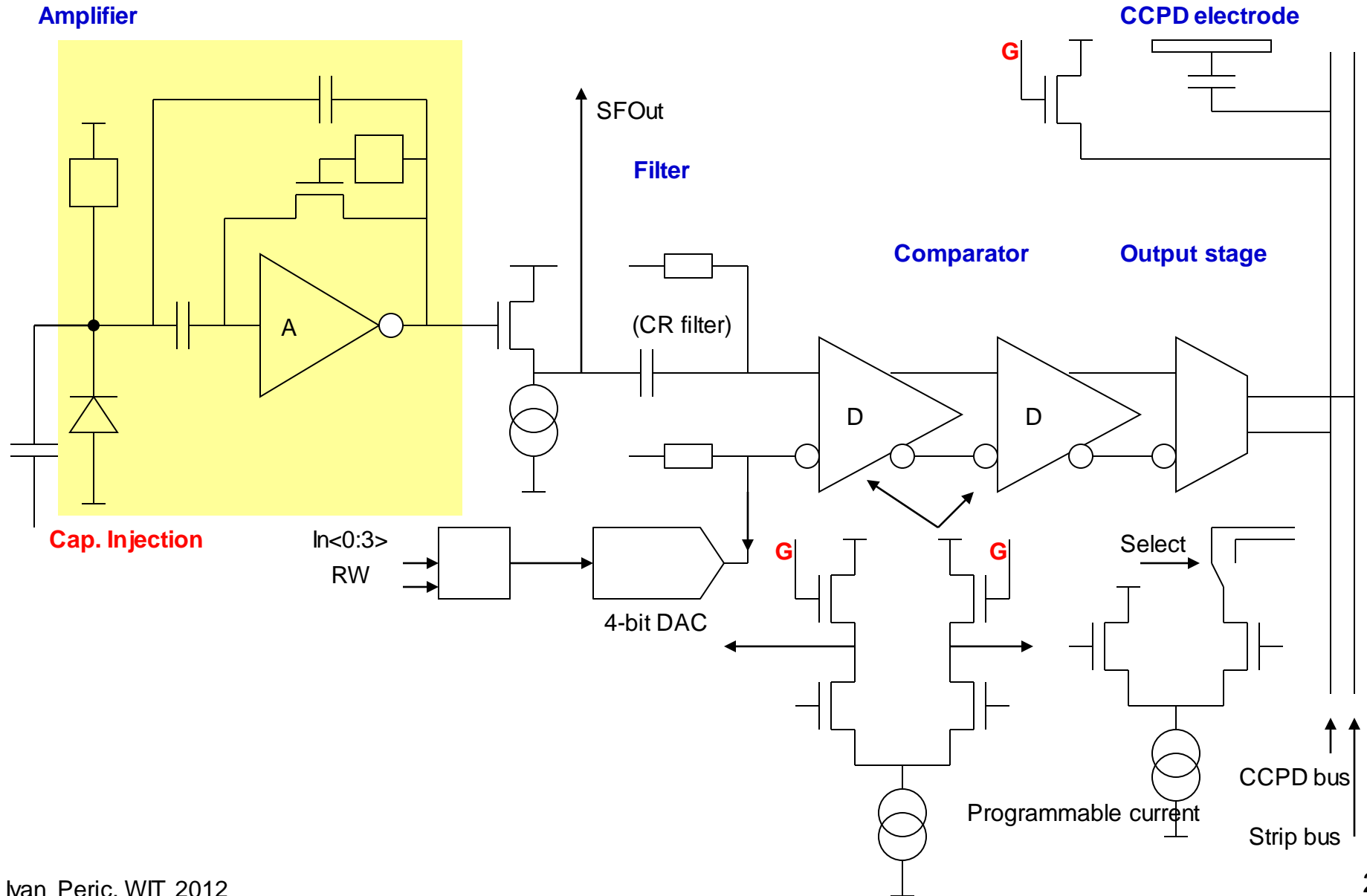


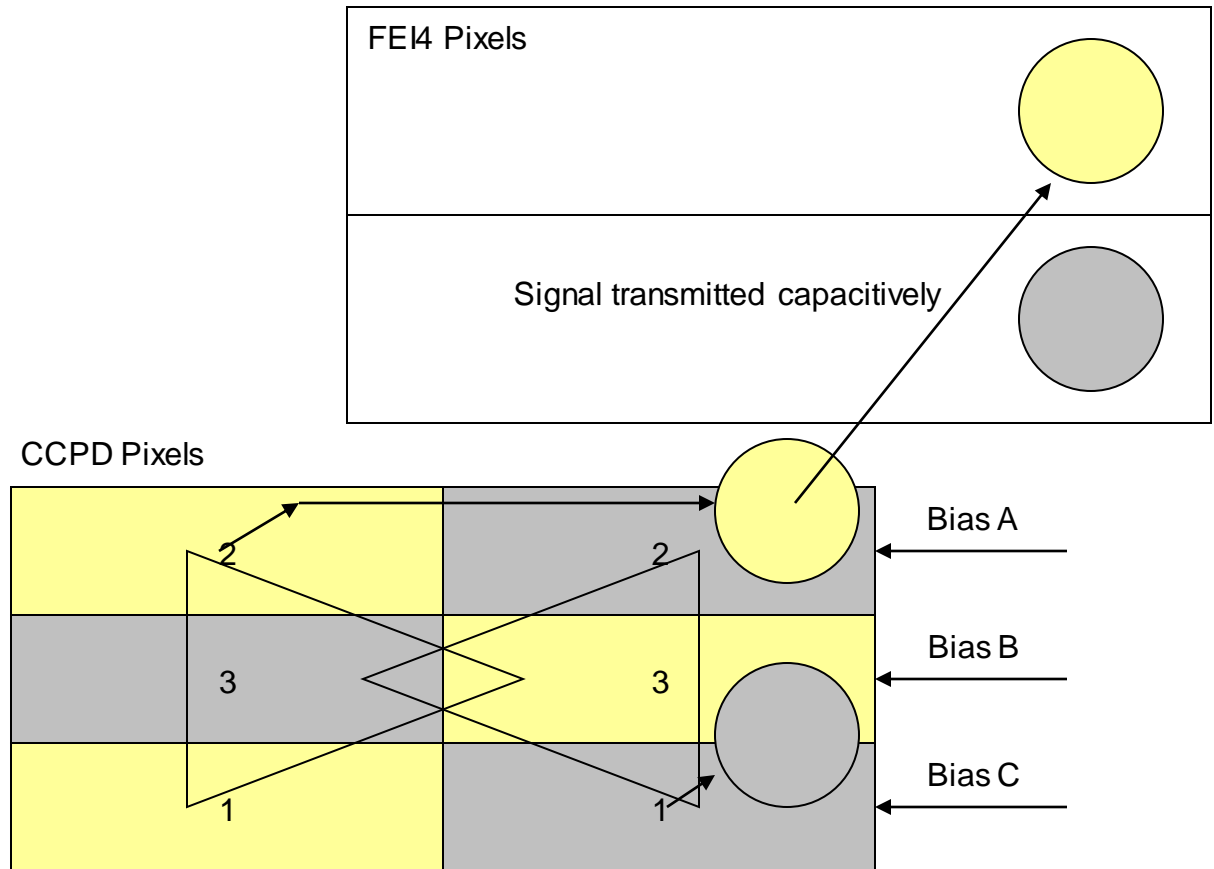
# Test Chip HV2FEI4

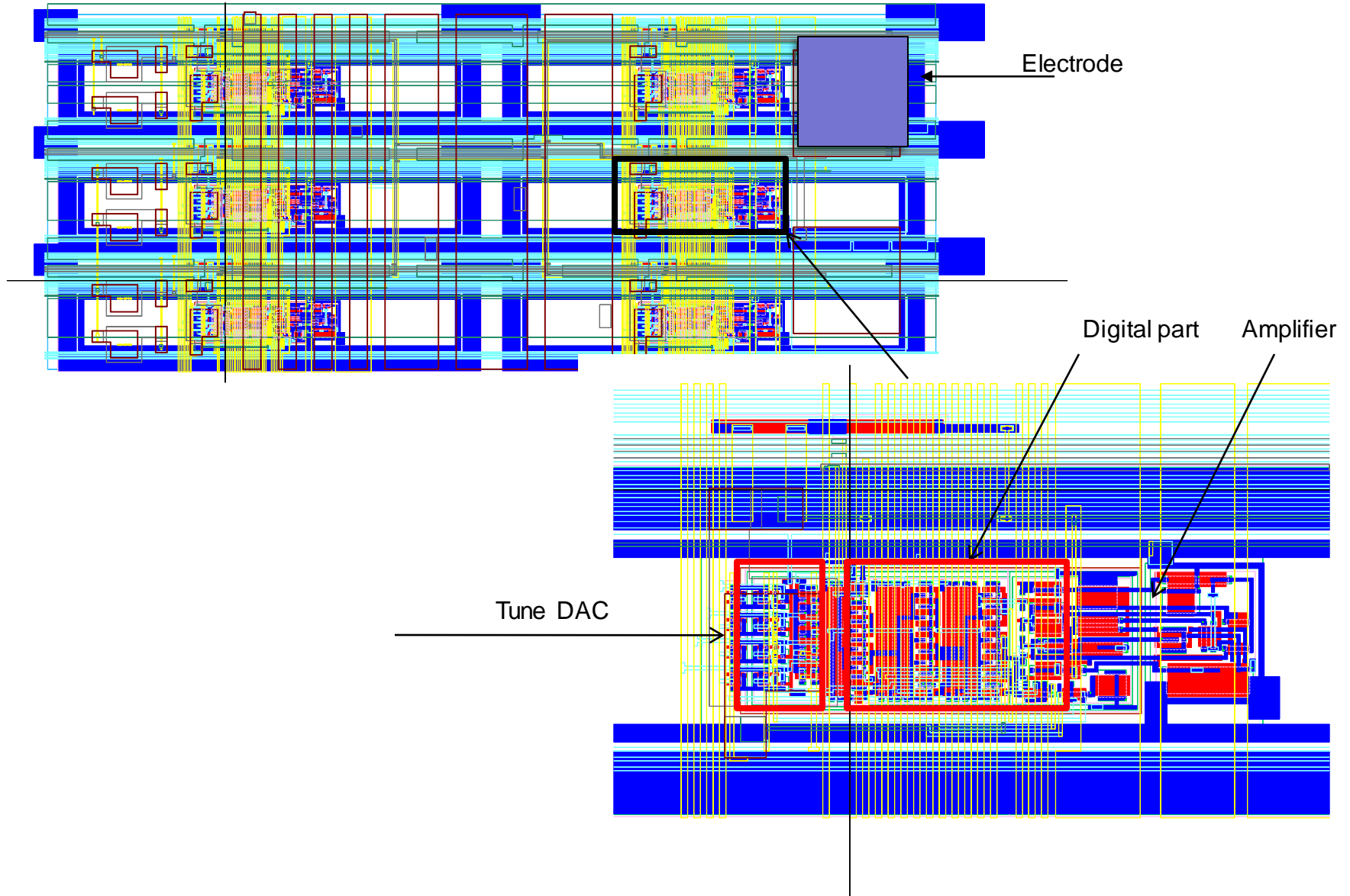


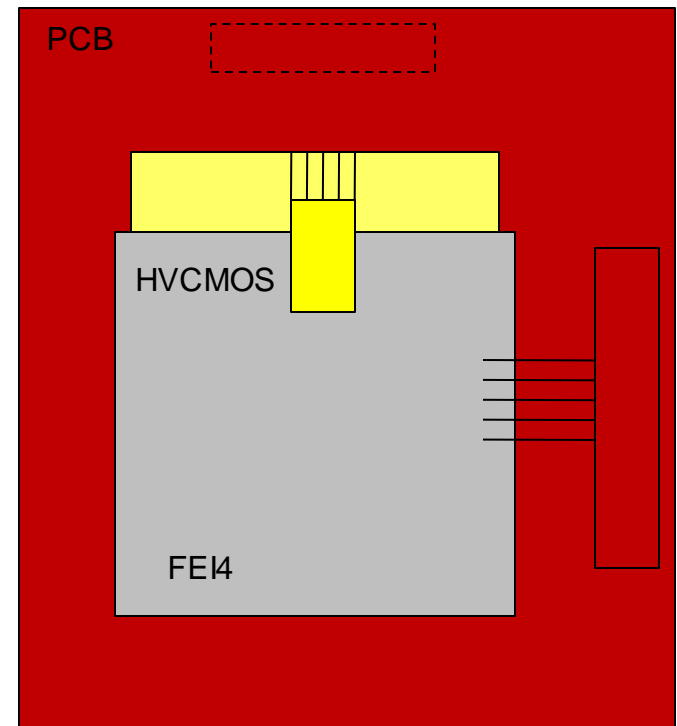
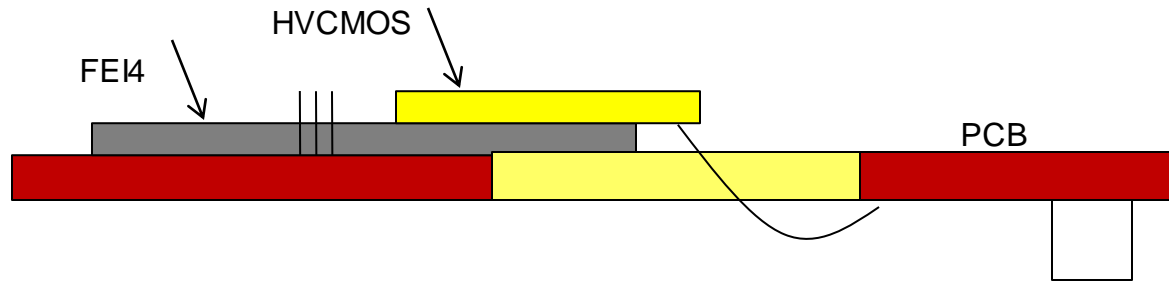
- Pixel matrix: 60x24 pixels
- Pixel size 33  $\mu\text{m}$  x 125  $\mu\text{m}$
- 21 IO pads at the lower side for CCPD operation
- 40 strip-readout pads (100  $\mu\text{m}$  pitch) at the lower side and 22 IO pads at the upper side for strip-operation
- Pixel contains charge sensitive amplifier, comparator and tune DAC
- We have received the chips last week – first results very soon.





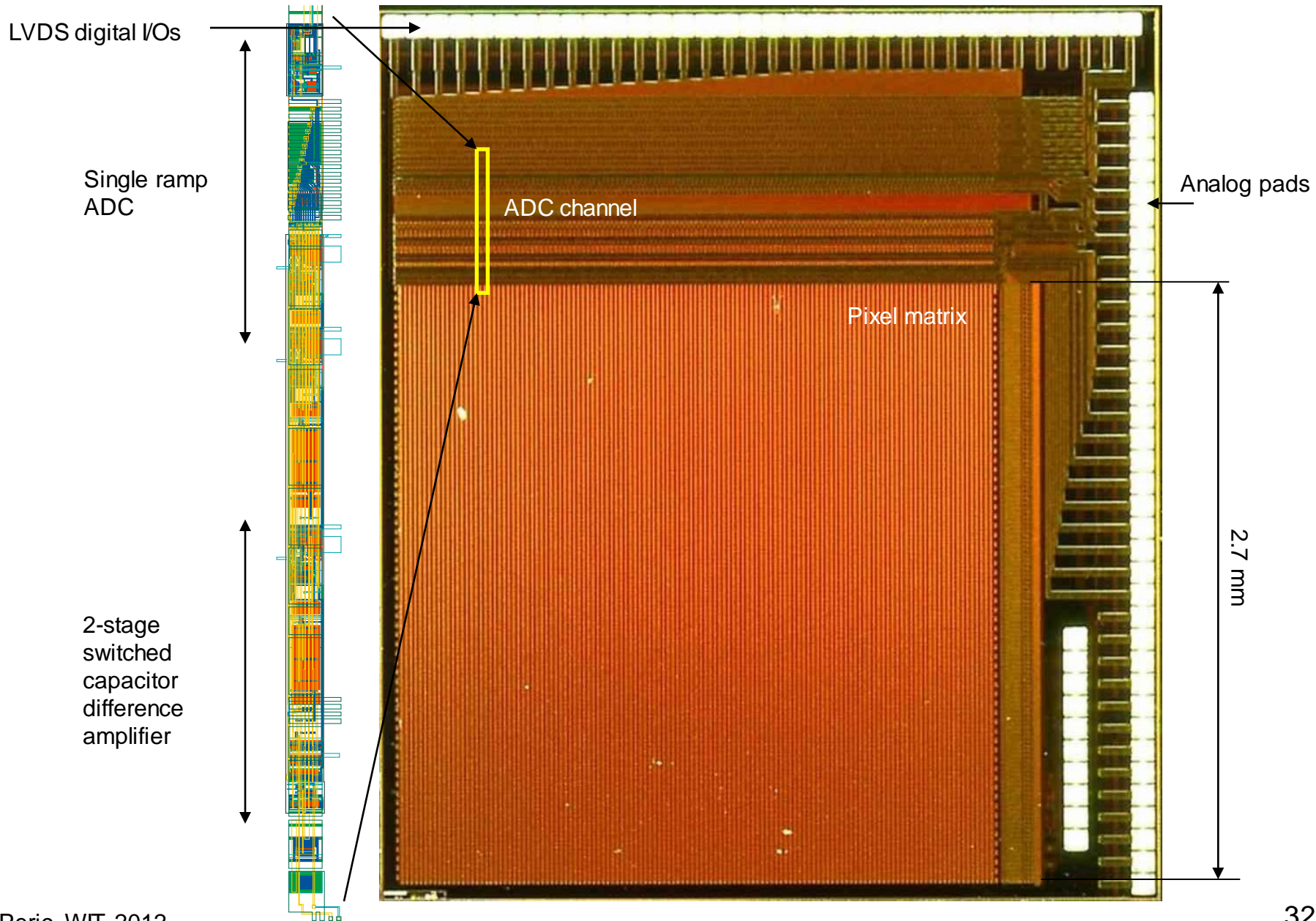






# Experimental Results with other Prototypes

# Efficiency and Signal Amplitude

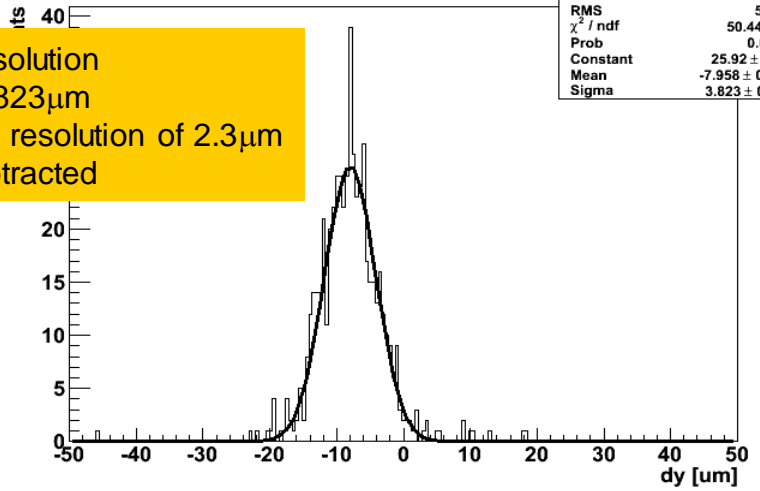




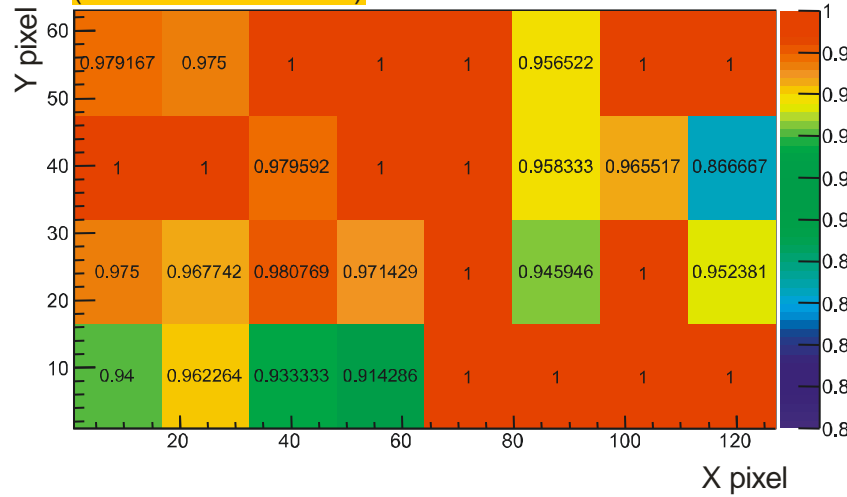
Hit Residuals Y

Spatial resolution  
Sigma:  $3.823\mu\text{m}$   
Telescope resolution of  $2.3\mu\text{m}$   
is not subtracted

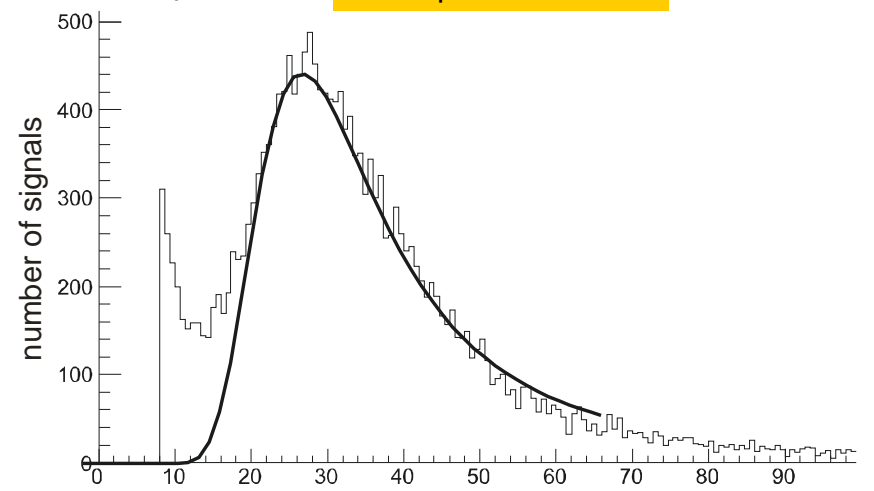
hy	
Entries	551
Mean	-7.974
RMS	5.094
$\chi^2 / \text{ndf}$	50.44 / 55
Prob	0.6492
Constant	$25.92 \pm 1.50$
Mean	$-7.958 \pm 0.176$
Sigma	$3.823 \pm 0.141$

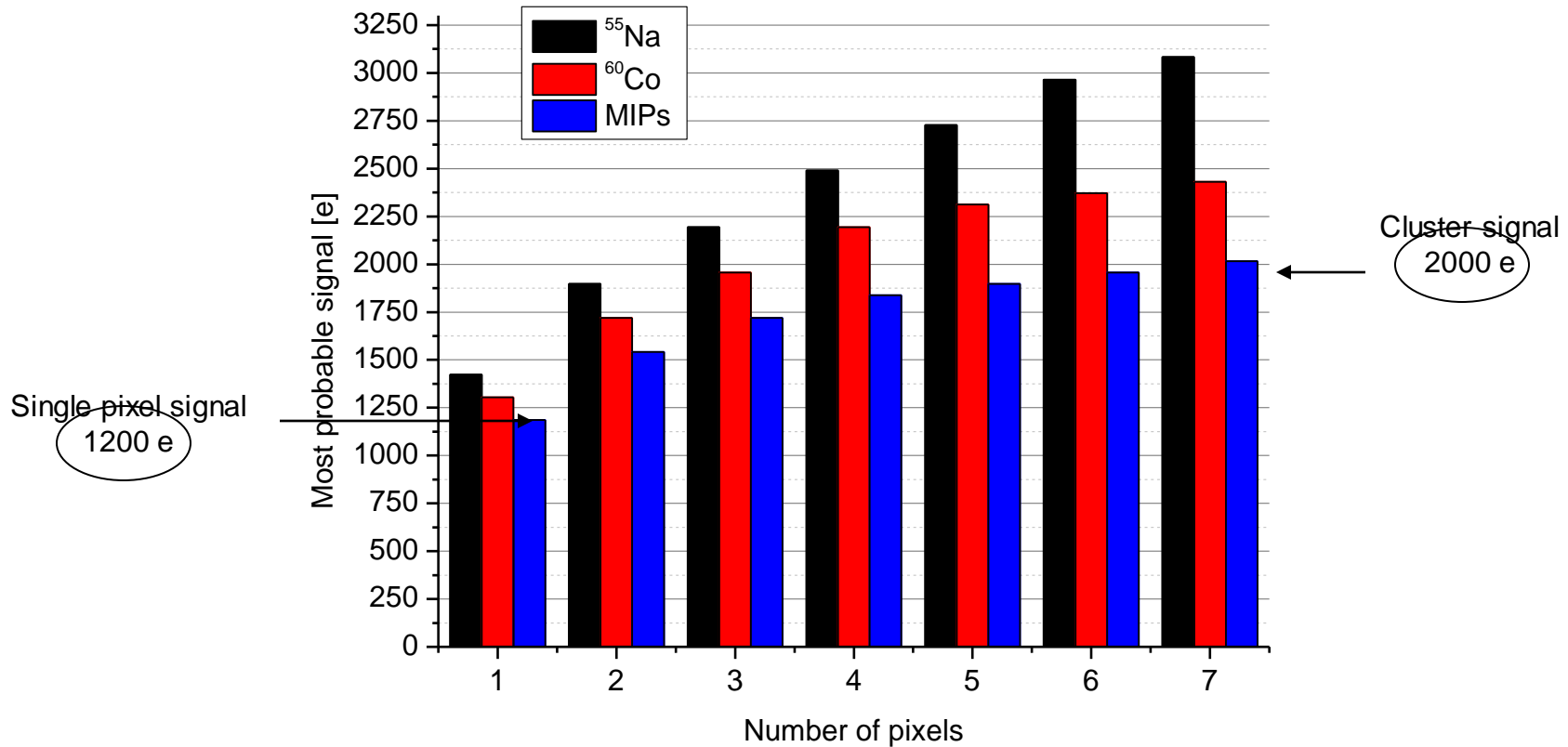


Efficiency vs pixel xy-coordinates  
(Mean value = 0.9761)



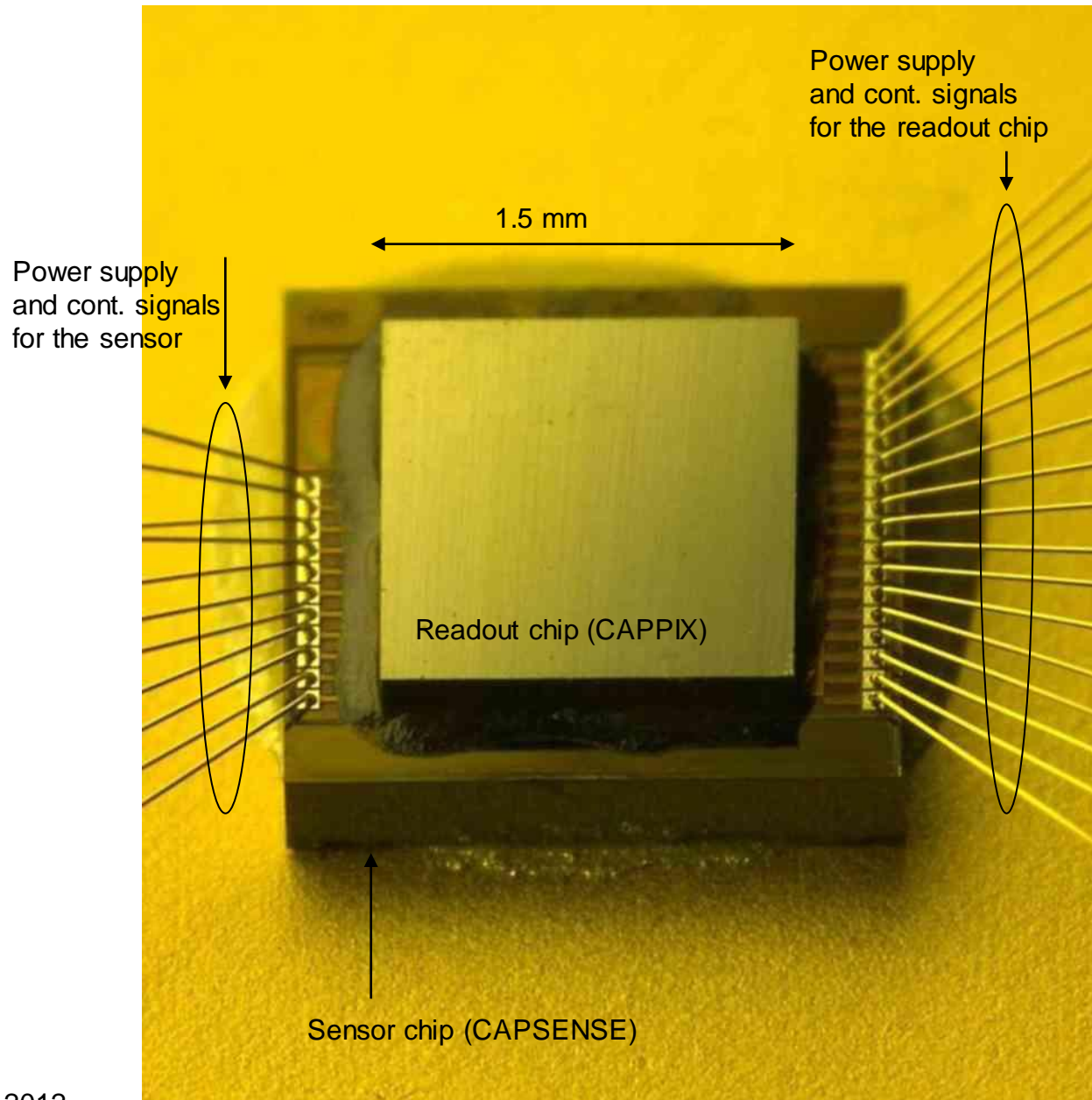
Seed pixel SNR      Seed pixel SNR = 27





High energy particle signals depending on number of pixels in cluster.

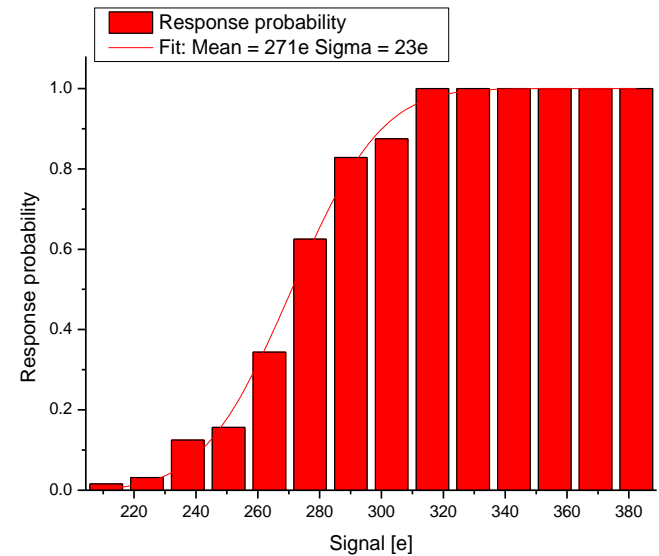
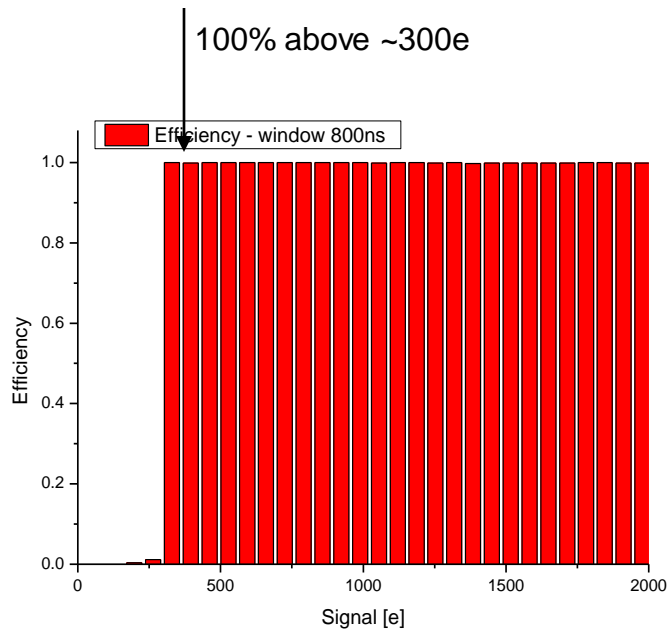
# CCPD Operation





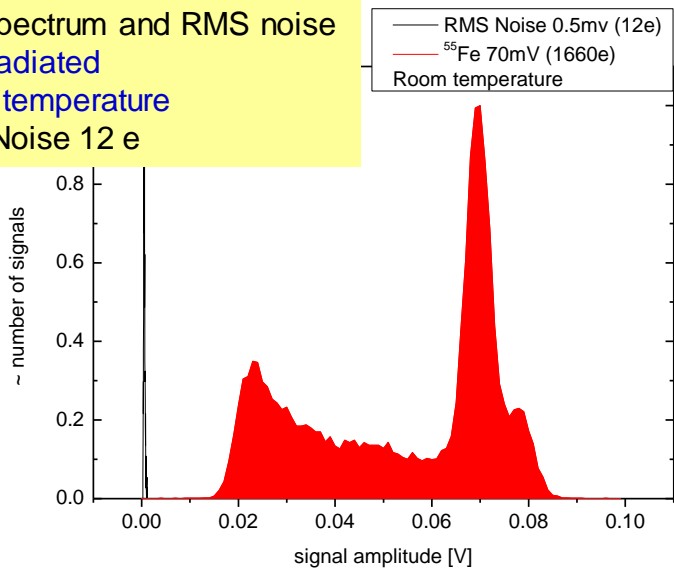
Response probability of all pixels in the matrix to test pulses that generate from 0 to 2000 electrons

Threshold scan used to measure noise – noise 23e

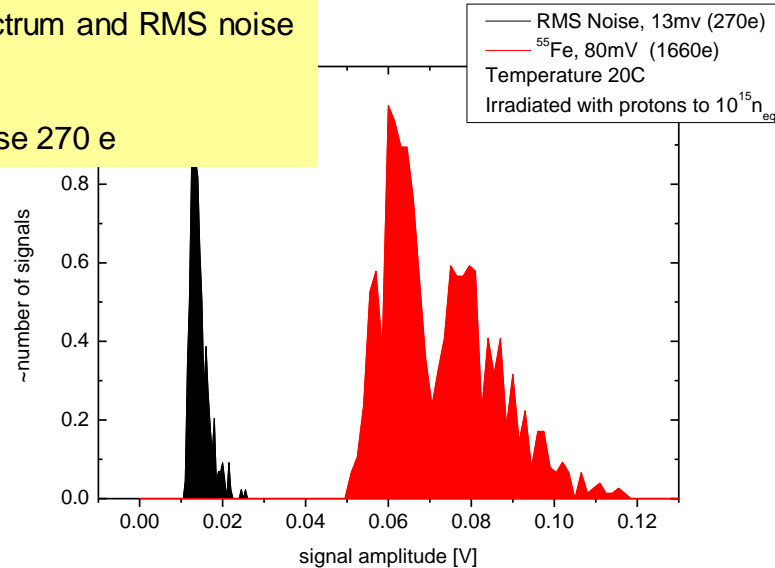


# Radiation Tolerance (CCPD2 Sensor)

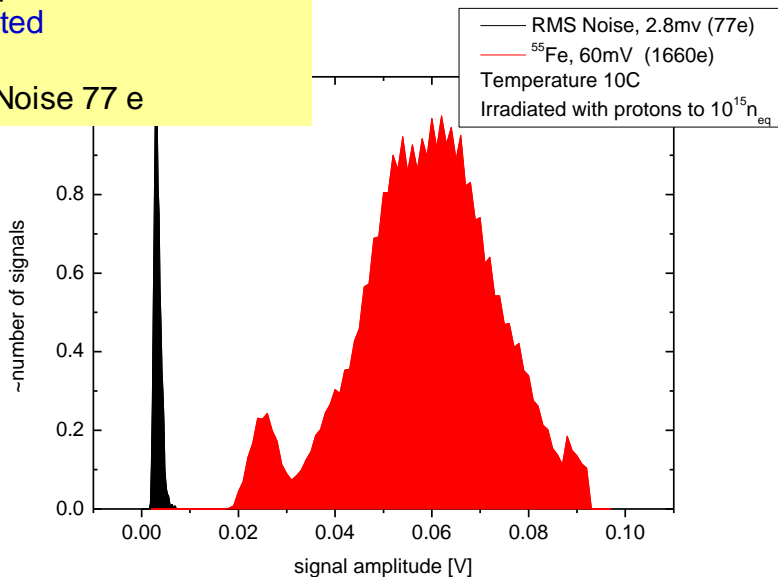
**$^{55}\text{Fe}$  spectrum and RMS noise**  
**Not irradiated**  
**Room temperature**  
**RMS Noise 12 e**



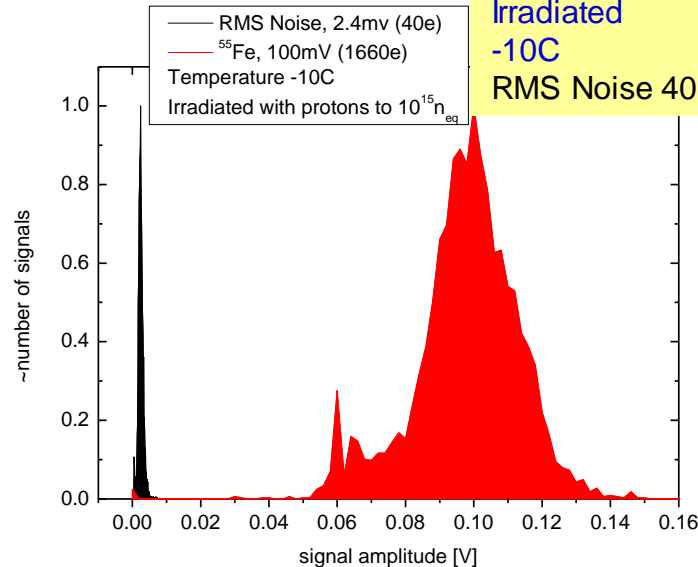
**$^{55}\text{Fe}$  spectrum and RMS noise**  
**Irradiated**  
**20C**  
**RMS Noise 270 e**



**$^{55}\text{Fe}$  spectrum, RMS noise**  
**Irradiated**  
**10C**  
**RMS Noise 77 e**



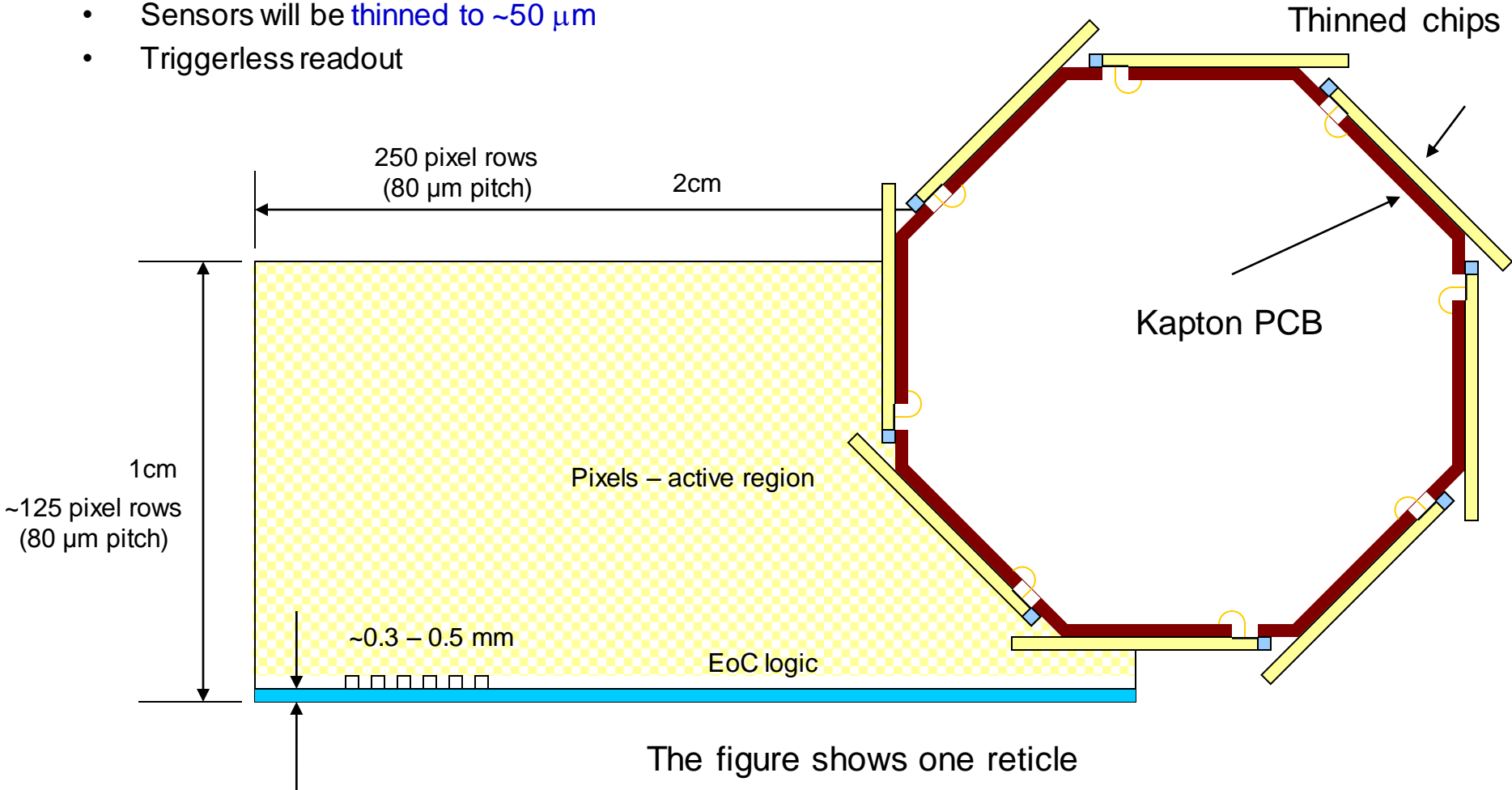
**$^{55}\text{Fe}$  spectrum, RMS noise**  
**Irradiated**  
**-10C**  
**RMS Noise 40 e**



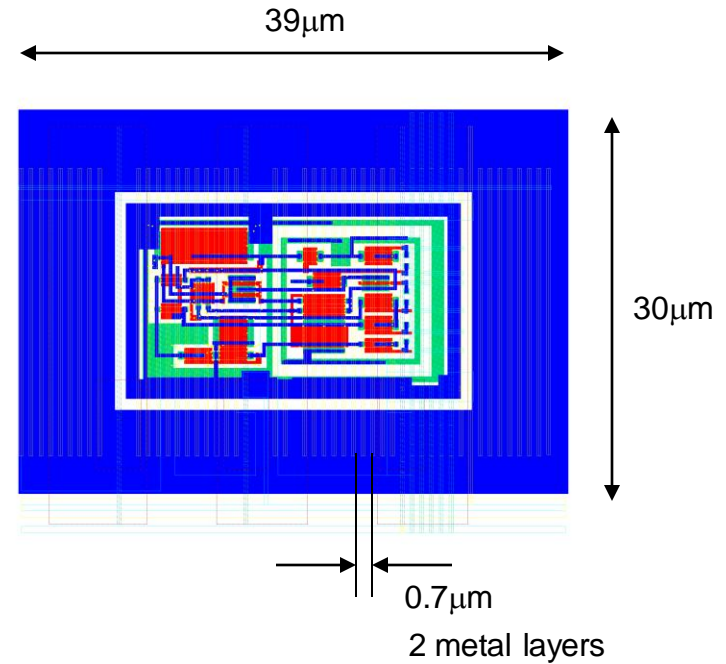
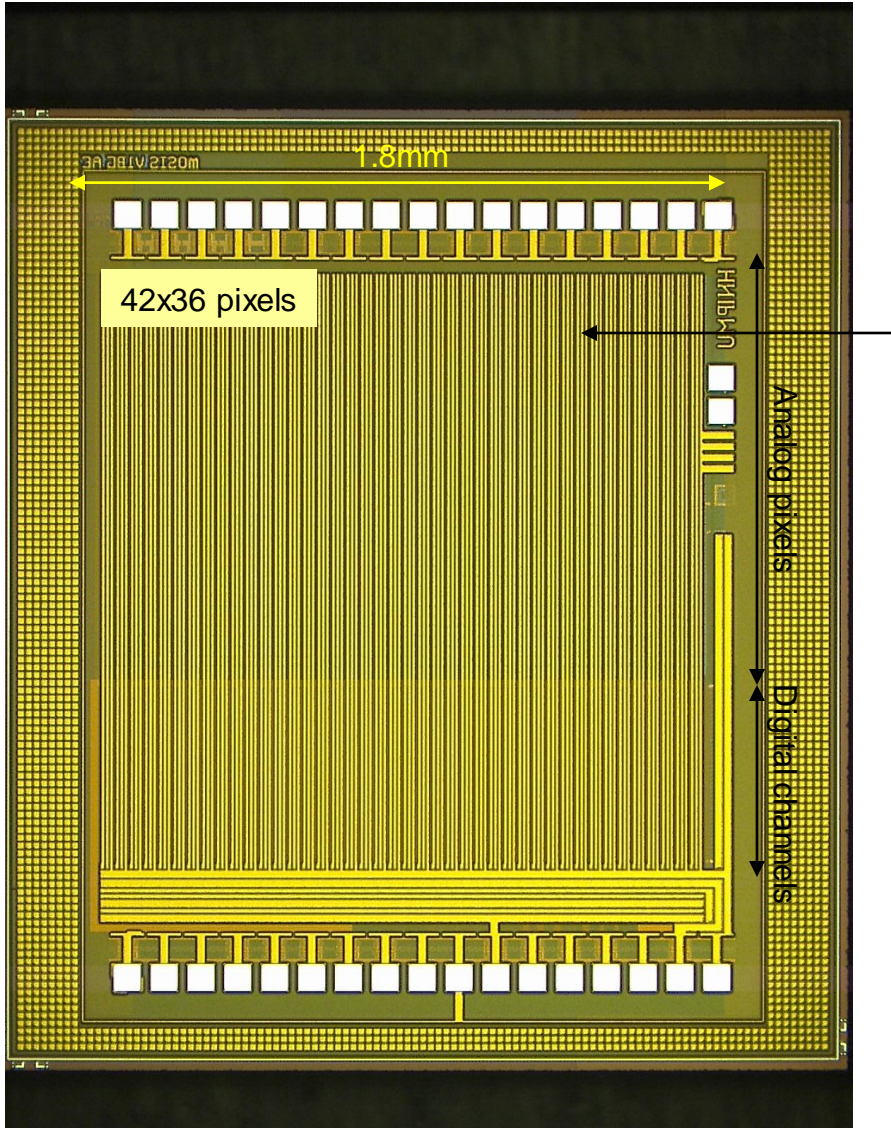
# Time Resolution



- Mu3e experiment at PSI (study of the lepton flavor violating decay  $\mu \rightarrow e e e$ )
- Proposed: four layers of pixels  $\sim 80 \times 80 \mu\text{m}^2$  size – monolithic pixel detector in HVCMOS technology
- Time stamping with  $< 100\text{ns}$  resolution required to reduce the number of tracks in an image.
- Sensors will be thinned to  $\sim 50 \mu\text{m}$
- Triggerless readout



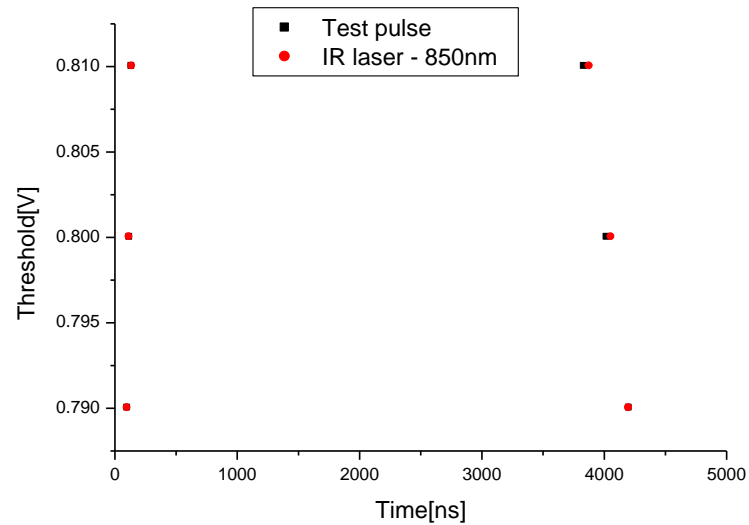
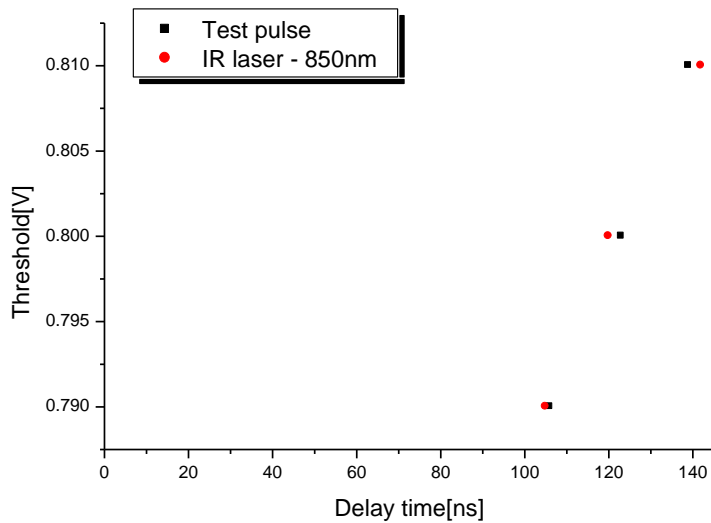
- More details can be seen in poster session:
- Dirk Wiedner: “A tracker for the novel mu3e experiment based on high voltage monolithic active pixel sensors”



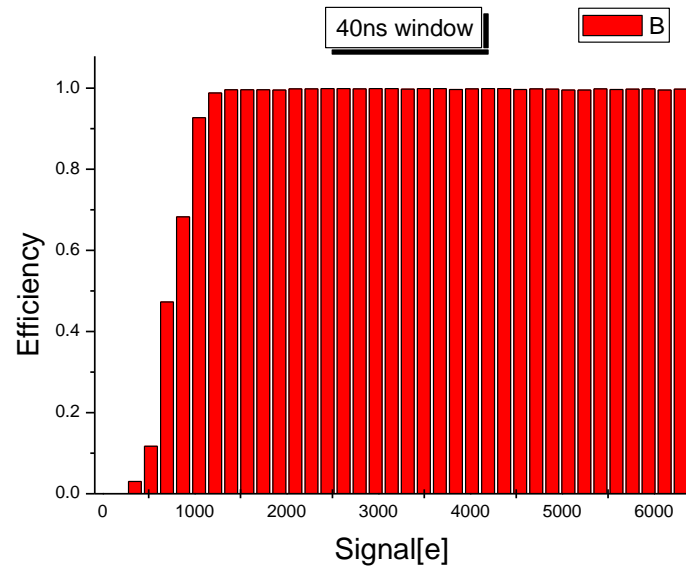
## Analog pixel layout

- Pixel detector chip with CMOS pixel (42x40 pixels) matrix
- Pixel size 39x30 micrometers
- Separated digital and analog block
- Signal time measurements possible

- Charge collection time – IR laser, comparison with the fast capacitive injection.
- No measurable delay versus the capacitive test pulse.

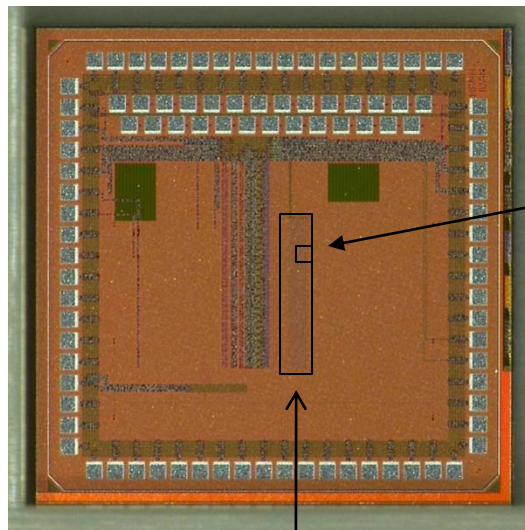


- In-time efficiency vs. signal amplitude (40ns time window)
- Detection of signals  $> 1230$  e with 40ns time resolution possible.
- Power consumption of the pixel  $7.5\mu\text{m}$ .

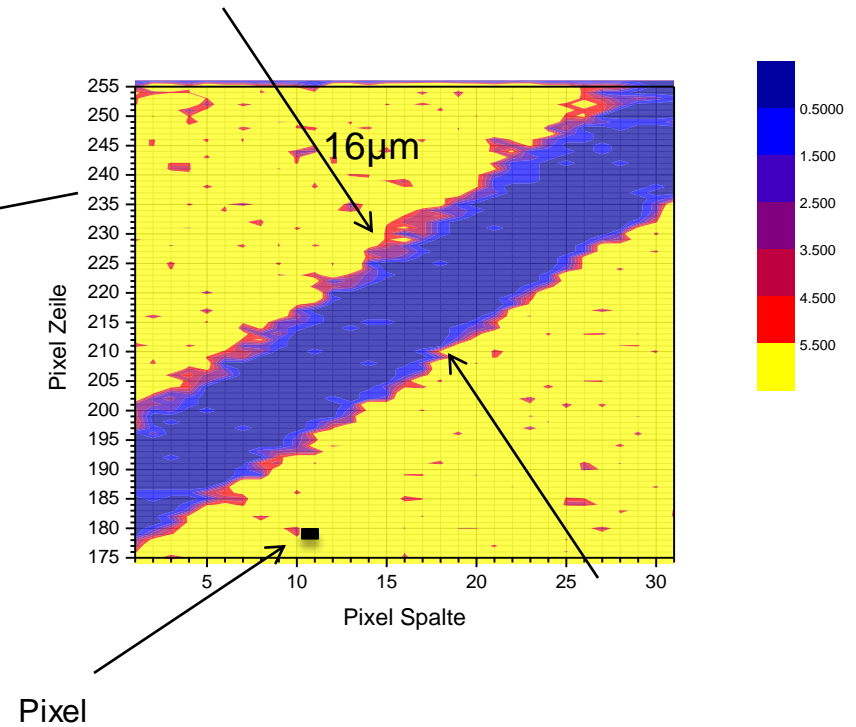


- Pixel size -  $2.5\mu\text{m}$

$^{55}\text{Fe}$  measurement  
Shadow of  $16\mu\text{m}$  thick golden bonding wire



Pixel matrix (32x256)



**HVPixel1 – CMOS in-pixel electronics with hit detection**

Binary RO

Pixel size 55x55 $\mu\text{m}$

Noise 60e

**MIP seed pixel signal 1800 e**

Time resolution 200ns

**Capacitive coupled hybrid detector**

**CCPD2 -capacitive coupled pixel detector**

Pixel size 50x50 $\mu\text{m}$

Noise 30-40e

Time resolution 300ns

**MIP SNR 45-60**

**Irradiations of test pixels**

**60MRad – MIP SNR 22 at 10C (CCPD1)**

**$10^{15}n_{eq}$  MIP SNR 50 at 10C (CCPD2)**

HV2FEI4 chip (first test next week!!!)

**CCPD for ATLAS pixel detector**

Readout with FEI4 chip

**Reduced pixel size: 33x125 $\mu\text{m}$**

RO type: capacitive and strip like

3 pixels connected to one FEI channel

**Monolithic detector –  
continuous readout  
with time measurement**

MuPixel –

**Monolithic pixel sensor for  
Mu3e experiment at PSI**

Charge sensitive amplifier in  
pixels

Hit detection, zero suppression  
and time measurement at chip  
periphery

Pixel size: 39x30  $\mu\text{m}$  (test chip)  
(80 x 80  $\mu\text{m}$  required later)

MIP seed signal 1500e (expected)

Noise: ~40 e (measured)

**Time resolution < 40ns**

**Power consumption**

**7.5 $\mu\text{W}$ /pixel**

**Monolithic detector -  
frame readout**

PM2 chip - frame mode readout

Pixel size 21x21 $\mu\text{m}$

4 PMOS pixel electronics

128 on-chip ADCs

Noise: 21e (lab) - 44e (test beam)

MIP signal - cluster: 2000e/seed: 1200e

Test beam: **Detection efficiency >98%**

**Seed Pixel SNR ~ 27**

Cluster signal/seed pixel noise ~ 47

**Spatial resolution ~ 3.8  $\mu\text{m}$**

**HPixel - frame mode readout  
In-pixel CMOS electronics with CDS**

128 on-chip ADCs

Pixel size 25x25  $\mu\text{m}$

Noise: 60e (preliminary)

MIP signal - cluster: 2100e/seed: 1000e  
(expected)

SDS - frame mode readout

**Pixel size 2.5x2.5  $\mu\text{m}$**

4 PMOS electronics

Noise: 20e (preliminary)

MIP signal (~1000e - estimation)

1. Technology 350nm HV – substrate 20  $\Omega\text{cm}$  uniform

2. Technology 180nm HV – substrate 10  $\Omega\text{cm}$  uniform

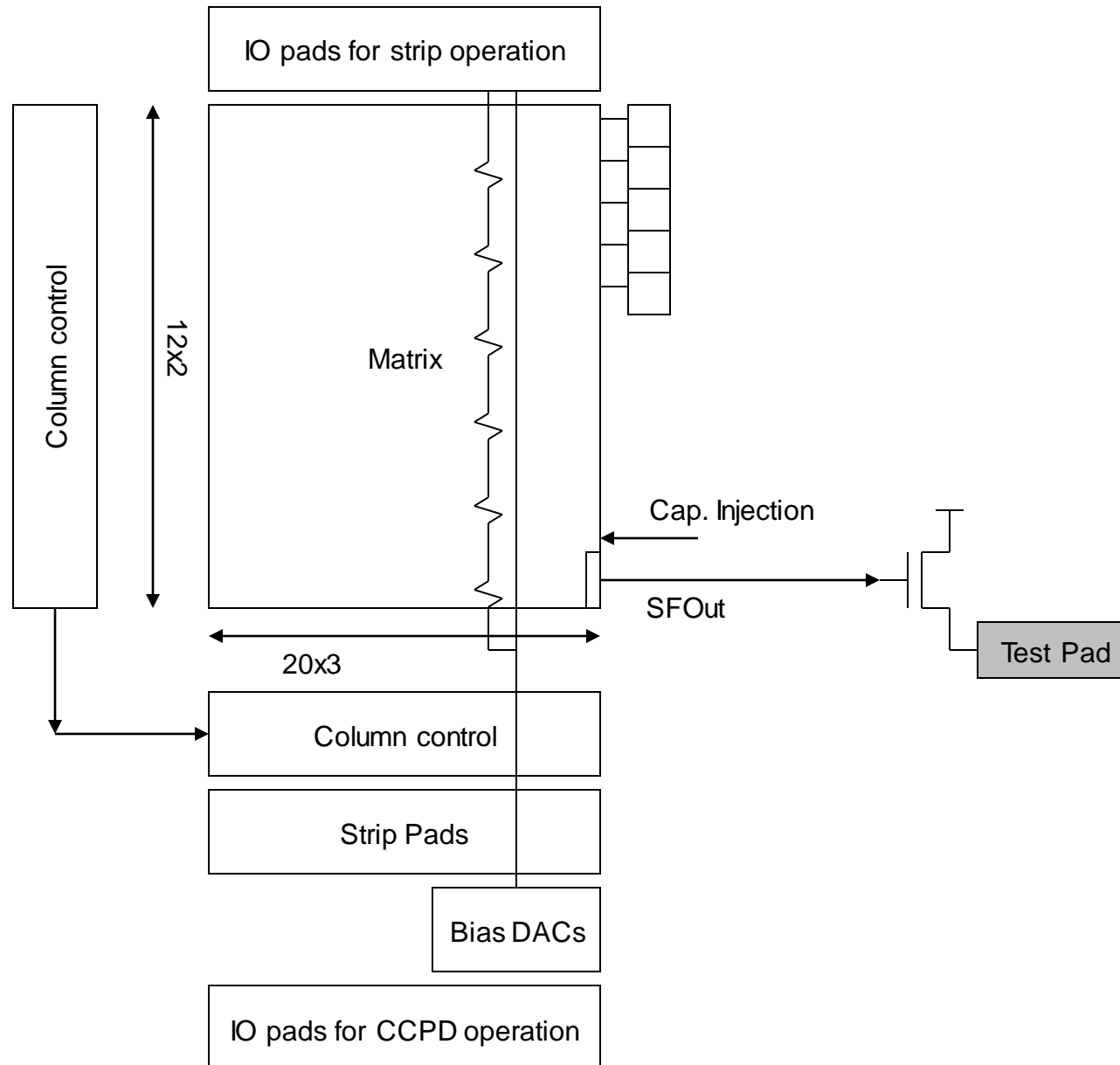
3. Technology 65nm LV – substrate 10  $\Omega\text{cm}$ /10  $\mu\text{m}$  epi

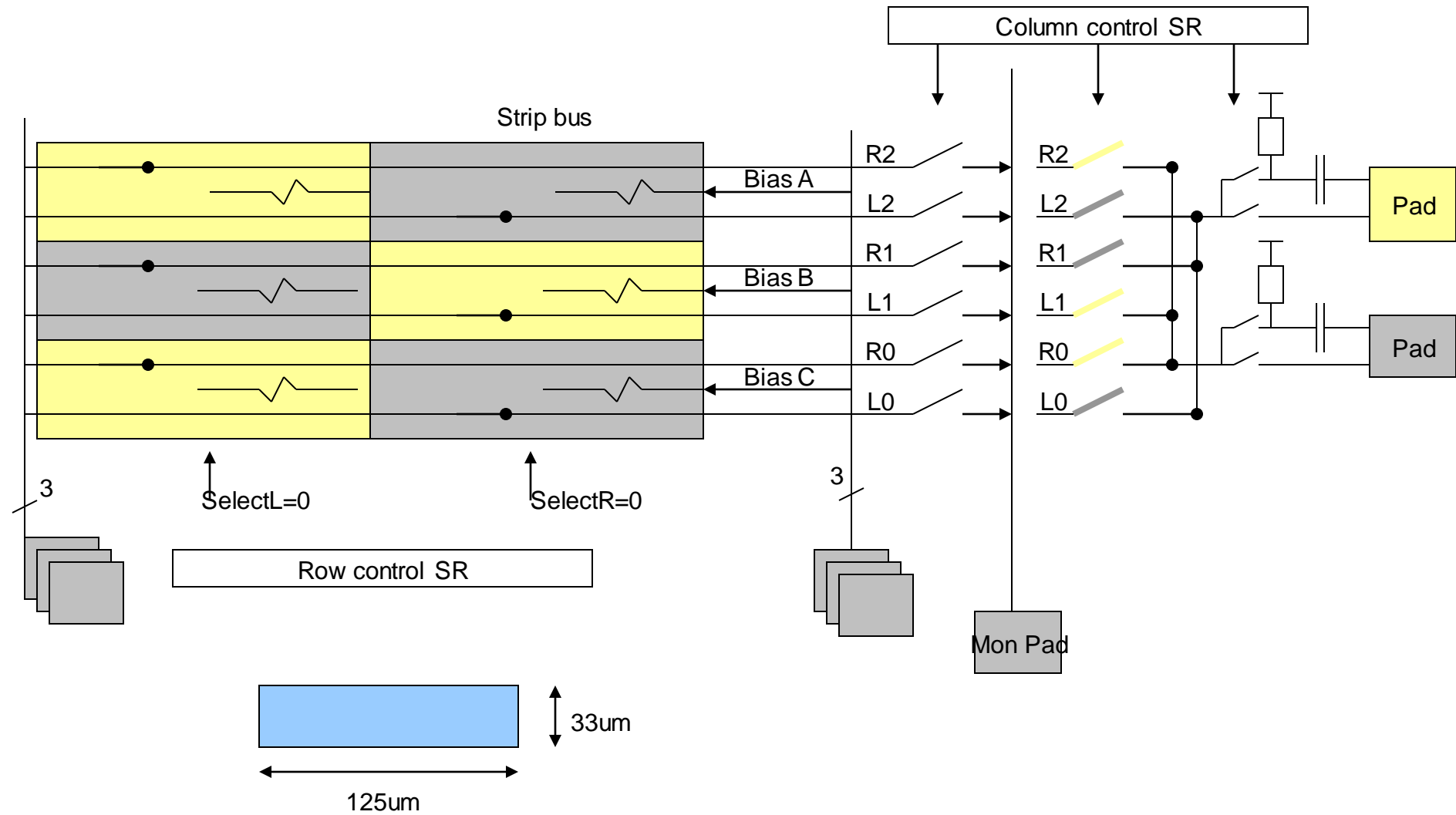
- We have developed a new pixel sensor structure (smart diode array) for high energy physics that is implemented in **high voltage CMOS technologies**.
- The advantages over conventional silicon sensors include **lower cost, lower mass, lower operating voltage, smaller pitch, and smaller clusters at high incidence angles, all with comparable radiation hardness**.
- We have implemented various test structures in 350nm and 180nm technologies and measured excellent detection and radiation properties.
- Measured time resolution < 40ns (IR laser), detection efficiency ~98% (test beam)
- Irradiated up to  $10^{15} n_{eq}/cm^2$  and dose 300MRad
- We would like to integrate our sensors into existing ATLAS readout systems, for this we have two concepts:
- Capacitive coupled pixel detectors -> readout with pixel readout chips like FEI4
- Strip-like sensors -> readout with strip readout AISCs
- **We have designed a test detector** (in 180nm HV CMOS technology) to test the two concepts – first measurements soon.

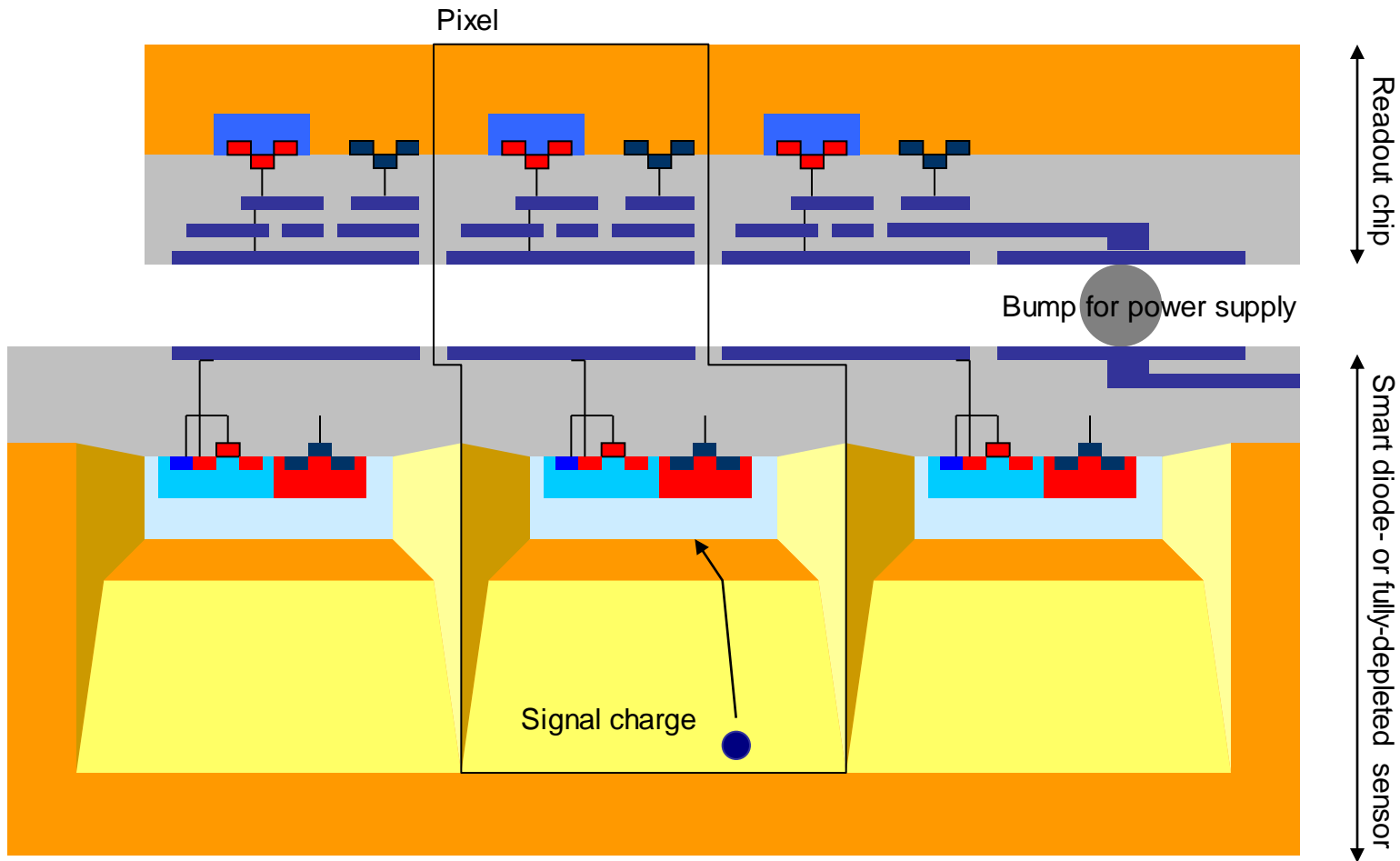


Thank you

# Backup Slides





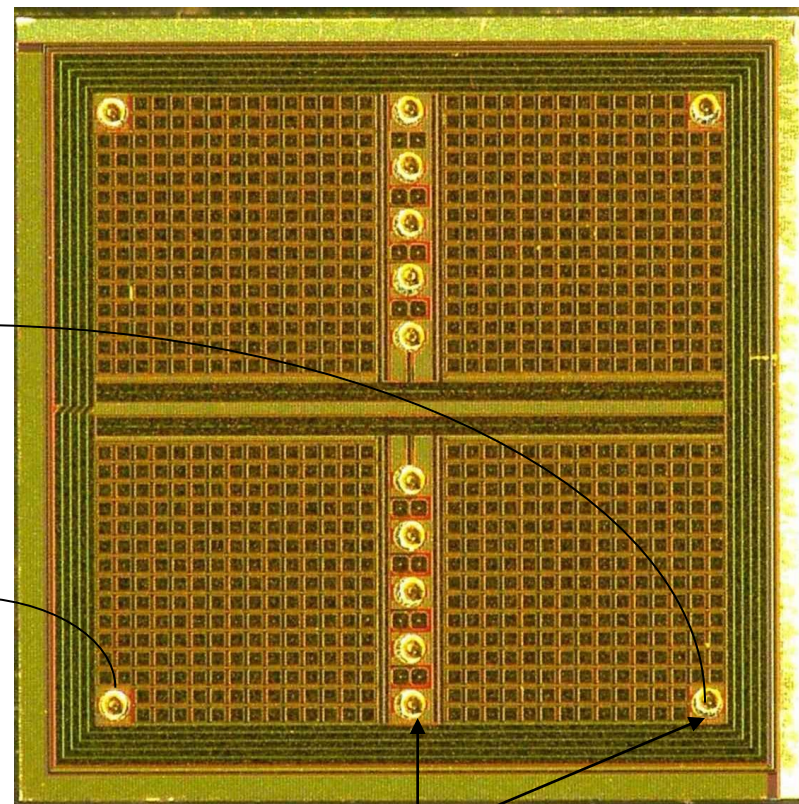
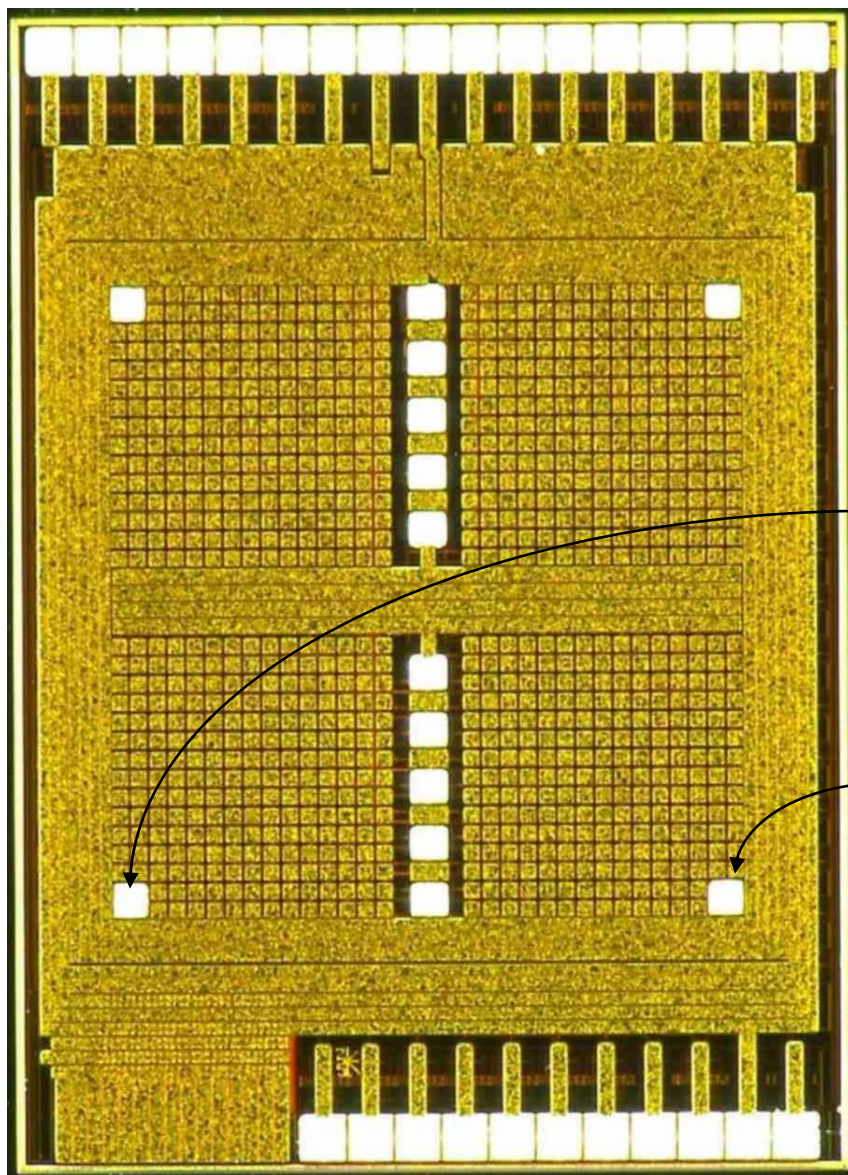


The sensor and readout chips are flipped and connected by a few bumps

Advantage – no need to wire-bond both chips

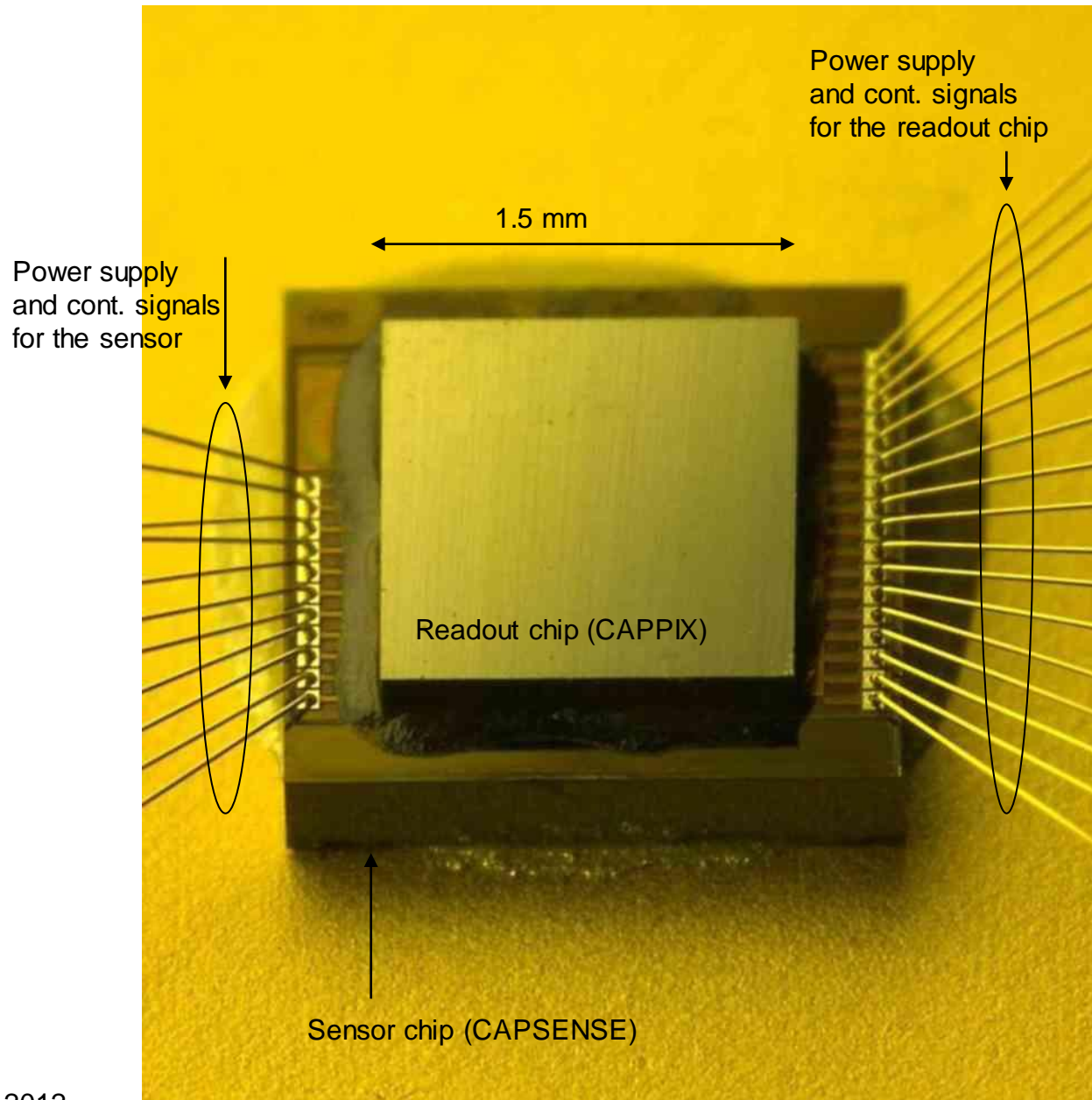
Power and signals for ROC provided by sensor chip

Edgeless sensor covered with many small ROCs can be made

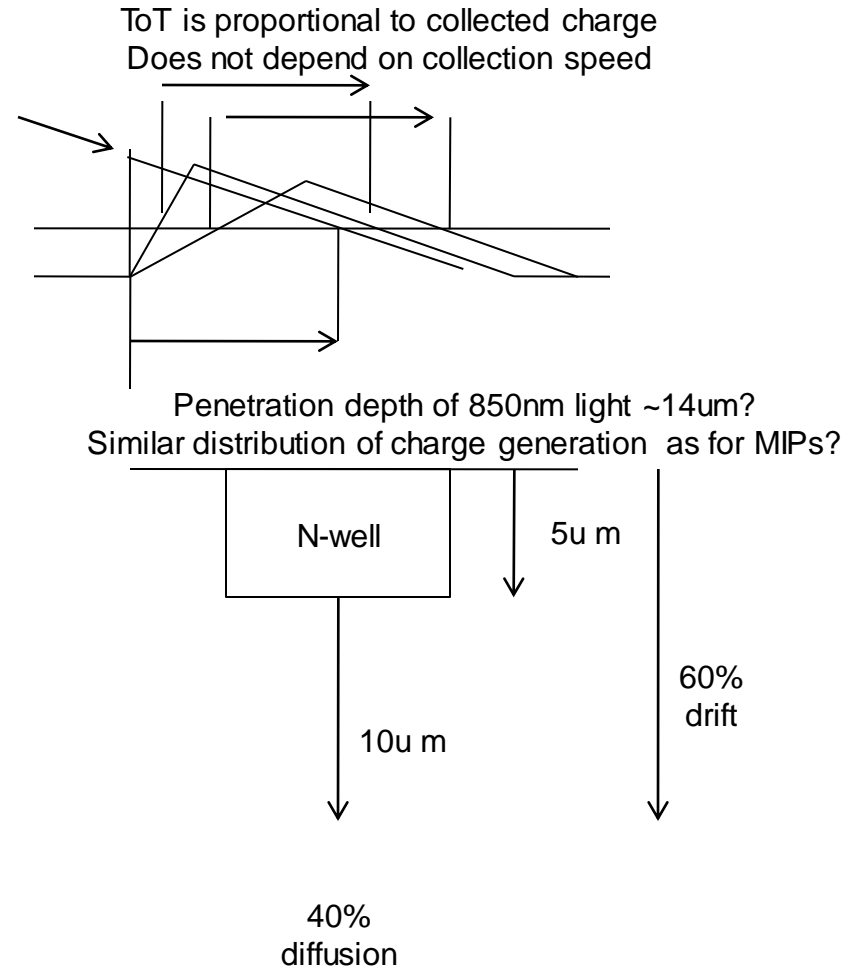
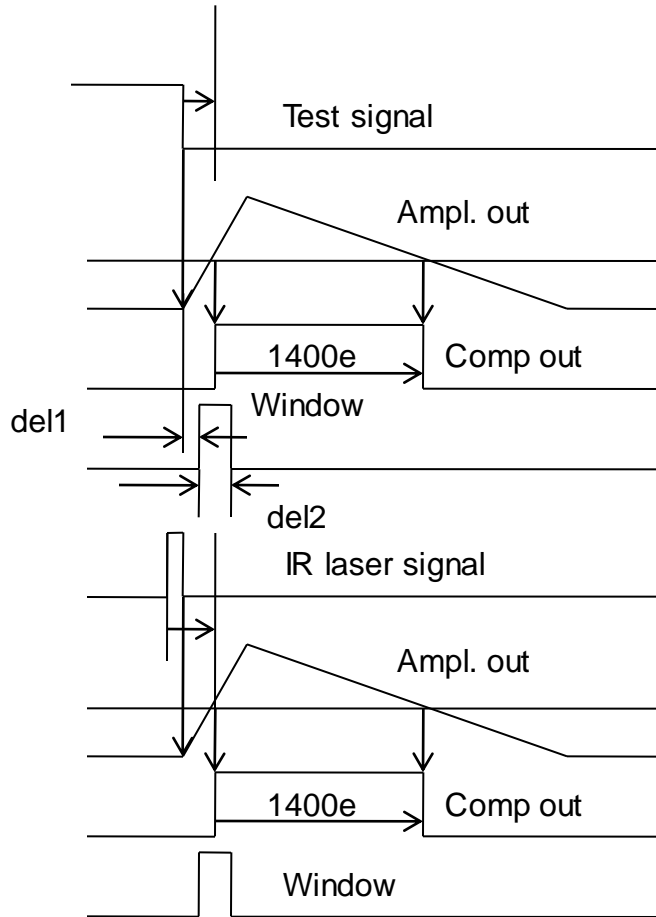


CAPPIX

Power and signal bumps



- Digital part





- Digital part

